

1  
2  
3  
4  
5  
6  
7  
8  
9

# Spontaneous Seed Formation During Electrodeposition Drives Epitaxial Growth of Metastable Bismuth Selenide Microcrystals

10 Jiang Luo<sup>1</sup>, Guodong Ren<sup>2</sup>, Brandon M. Campbell<sup>1</sup>, Dongyan Zhang<sup>1</sup>, Tengfei Cao<sup>3</sup>, Rohan  
11  
12 Mishra<sup>3,2\*</sup>, Bryce Sadtler<sup>1,2\*</sup>  
13

14  
15 <sup>1</sup> Department of Chemistry, Washington University, St. Louis, Missouri 63130, United States  
16

17 <sup>2</sup> Institute of Materials Science & Engineering, Washington University, St. Louis, Missouri 63130,  
18  
19 United States  
20

21 <sup>3</sup> Department of Mechanical Engineering & Materials Science, Washington University in St. Louis,  
22  
23 St. Louis, Missouri 63130, United States  
24

25 \* To whom correspondence should be addressed. Email: [rmishra@wustl.edu](mailto:rmishra@wustl.edu), [sadtler@wustl.edu](mailto:sadtler@wustl.edu)  
26  
27  
28  
29  
30  
31  
32  
33  
34  
35  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

## Abstract

Materials with metastable phases can exhibit vastly different properties from their thermodynamically favored counterparts. Methods to synthesize metastable phases without the need for high-temperature or high-pressure conditions would facilitate their widespread use. We report on the electrochemical growth of microcrystals of bismuth selenide,  $\text{Bi}_2\text{Se}_3$ , in the metastable orthorhombic phase at room temperature in aqueous solution. Rather than direct epitaxy with the growth substrate, the spontaneous formation of a seed layer containing nanocrystals of cubic BiSe enforces the metastable phase. We first used single-crystal silicon substrates with a range of resistivities and different orientations to identify the conditions needed to produce the metastable phase. When the applied potential during electrochemical growth is positive of the reduction potential of  $\text{Bi}^{3+}$ , an initial, Bi-rich seed layer forms. Electron microscopy imaging and diffraction reveal that the seed layer consists of nanocrystals of cubic BiSe embedded within an amorphous matrix of Bi and Se. Using density-functional theory calculations, we show that epitaxial matching between cubic BiSe and orthorhombic  $\text{Bi}_2\text{Se}_3$  can help stabilize the metastable orthorhombic phase over the thermodynamically stable rhombohedral phase. The spontaneous formation of the seed layer enables us to grow orthorhombic  $\text{Bi}_2\text{Se}_3$  on a variety of substrates including single-crystal silicon with different orientations, polycrystalline fluorine-doped tin oxide, and polycrystalline gold. The ability to stabilize the metastable phase through room-temperature electrodeposition in aqueous solution without requiring a single-crystal substrate, broadens the range of applications for this semiconductor in optoelectronic and electrochemical devices.

## Introduction

Many metastable materials exhibit promising catalytic, electronic, and optical properties, that make them attractive for applications in the conversion and storage of energy and information, including as electro- and photocatalysts for fuel generation,<sup>1-4</sup> electrodes for metal-air batteries,<sup>5-6</sup> and qubits for quantum computation.<sup>7-8</sup> Compared to their corresponding ground-state structures, metastable materials have a higher formation energy and are thus often difficult to synthesize under ambient conditions. For example, naturally occurring diamond forms at high pressures and temperatures. Innovations in the synthesis and doping of diamond via chemical vapor deposition<sup>9-11</sup> have enabled fundamental studies of nitrogen vacancies in this metastable material for applications in quantum sensing and computation.<sup>7-8, 12</sup>

Methods to synthesize metastable phases at moderate pressure and temperature include colloidal synthesis,<sup>5, 13-14</sup> chemical and physical vapor deposition,<sup>6, 9-11</sup> solid-state metathesis,<sup>15-16</sup> and electrodeposition.<sup>3, 17-25</sup> Electrodeposition is particularly attractive because it is a versatile and inexpensive method to produce metals,<sup>3, 17-20</sup> ceramics,<sup>21, 26</sup> and semiconductors<sup>22-25, 27-36</sup> at atmospheric pressure and temperatures below 100°C. Although many binary metallic alloys and intermetallic compounds with metastable structures have been prepared by electrodeposition,<sup>3, 17-20</sup> there only exist a few examples of electrodepositing metastable phases of semiconductor compounds including Bi<sub>2</sub>Se<sub>3</sub>,<sup>23-25</sup> CdSe,<sup>22</sup> and  $\delta$ -Bi<sub>2</sub>O<sub>3</sub>.<sup>21</sup> To achieve high crystallinity during the electrodeposition of compounds with significant covalent bonding character, a single-crystal growth substrate is often required that provides epitaxial matching between the substrate surface (i.e., the working electrode of the electrochemical cell) and the structure of the desired phase. For example, both the zinc blende phase of CdSe (which is metastable relative to the wurtzite phase at room temperature) and the cubic  $\delta$  phase of Bi<sub>2</sub>O<sub>3</sub> (which is metastable relative to the monoclinic  $\alpha$

phase at room temperature) can be electrodeposited on single-crystal Au (111) substrates.<sup>21-22</sup> The requirement for a single-crystal substrate limits the scale up and commercial application of electrodeposition to achieve phase control and synthesize desirable metastable phases of ceramics and semiconductor compounds.<sup>37</sup>

Bismuth chalcogenides have been proposed as materials for photodetectors and photovoltaics,<sup>23, 38-40</sup> thermoelectrics,<sup>41-44</sup> and topological insulators.<sup>45-46</sup> The structures of bismuth chalcogenide compounds vary with the identity of the chalcogen atom. For example, the thermodynamically stable phase of  $\text{Bi}_2\text{Se}_3$ , which is isomorphic with  $\text{Bi}_2\text{Te}_3$  and  $\text{Sb}_2\text{Te}_3$ , has a layered, rhombohedral crystal structure, as shown in **Figure 1a**. Rhombohedral  $\text{Bi}_2\text{Se}_3$  with a narrow band gap of 0.35 eV has been proposed as a topological insulator.<sup>45-46</sup> The metastable phase of  $\text{Bi}_2\text{Se}_3$  has an orthorhombic crystal structure, as shown in **Figure 1b**. Orthorhombic  $\text{Bi}_2\text{Se}_3$  is isomorphic with  $\text{Sb}_2\text{S}_3$  (i.e., stibnite),  $\text{Sb}_2\text{Se}_3$ , and  $\text{Bi}_2\text{S}_3$ ; it consists of zigzagging chains of  $[\text{BiSe}_5]$  pyramids and distorted  $[\text{BiSe}_6]$  octahedra that share edges along the [001] direction. The optical band gap of 1.25 eV for orthorhombic  $\text{Bi}_2\text{Se}_3$ <sup>23</sup> combined with its strong absorption in the visible region and anisotropic crystal structure make this material of interest for optoelectronic devices including polarization-sensitive photodetectors.<sup>38-39, 47-48</sup>

Films of  $\text{Bi}_2\text{Se}_3$  have previously been electrodeposited in both the rhombohedral and orthorhombic phases.<sup>23-25, 44, 49-55</sup> Electrodeposition on polycrystalline metal and metal oxide substrates (e.g., Au, Ru, Ti, Pt, stainless steel, or tin oxide) has produced films with the rhombohedral phase, a mixture of the two phases, or the orthorhombic phase with low crystallinity (i.e., films exhibiting small crystallite sizes and weak diffraction peaks).<sup>25, 44, 50-55</sup> Growth of phase-pure orthorhombic  $\text{Bi}_2\text{Se}_3$  with high crystallinity has been reported only when electrodeposited on single-crystal, *n*-type Si (100) substrates with relatively high resistivities of 4 to 30  $\Omega \times \text{cm}$ .<sup>23-25, 49</sup>

1  
2  
3 Thus, formation of the metastable, orthorhombic phase was proposed to result from direct epitaxy  
4 between the Si (100) substrate and the growing film. A unified mechanism for controlling the  
5 phase selectivity in this material system has not yet been developed. Furthermore, while  
6 orthorhombic  $\text{Bi}_2\text{Se}_3$  is of potential interest for optoelectronic and thermoelectric devices, the  
7 requirement to deposit on single-crystal Si substrates limits the ability to measure fundamental  
8 properties of this metastable material and determine its suitability for these applications.  
9  
10  
11  
12  
13  
14  
15

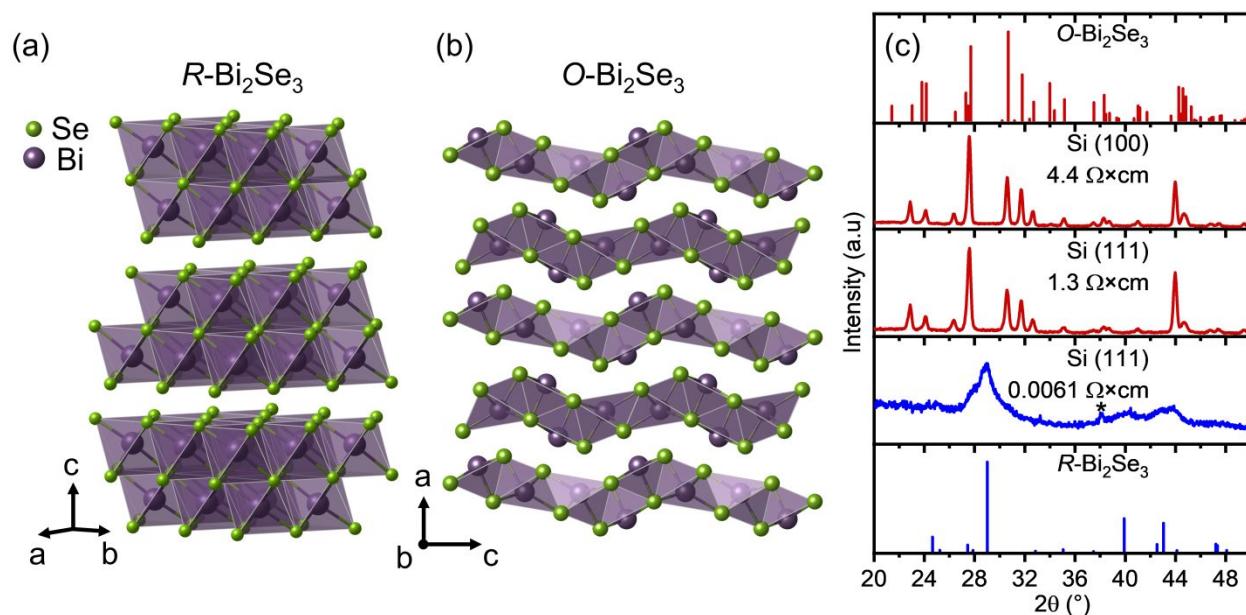
16 In this Article, we demonstrate that the spontaneous formation of a seed layer during the  
17 electrodeposition of bismuth selenide,  $\text{Bi}_2\text{Se}_3$ , enforces growth of the metastable orthorhombic  
18 phase through epitaxial strain. Seeded epitaxial growth enables us to electrodeposit this  
19 semiconductor with high crystallinity, which is not typically observed in electrodeposition. We  
20 first determined the phase of  $\text{Bi}_2\text{Se}_3$  films that were electrodeposited on single-crystal silicon  
21 substrates with a range of resistivities and different orientations. By varying the applied potential  
22 used to grow the films, we identified that formation of a previously unrecognized seed layer —  
23 with a distinct composition and structure from that of  $\text{Bi}_2\text{Se}_3$  — is necessary to produce the  
24 metastable orthorhombic phase. Through transmission electron microscopy, we uncovered that the  
25 seed layer contains nanocrystals of cubic  $\text{BiSe}$ . Orthorhombic  $\text{Bi}_2\text{Se}_3$  microcrystals nucleate from  
26 the  $\text{BiSe}$  nanocrystals and grow along the [010] direction. Our experimental results are supported  
27 by first-principles calculations that show the epitaxial strain between cubic  $\text{BiSe}$  and orthorhombic  
28  $\text{Bi}_2\text{Se}_3$  is much smaller than that between cubic  $\text{BiSe}$  and the thermodynamically stable,  
29 rhombohedral phase of  $\text{Bi}_2\text{Se}_3$ . This model of seeded epitaxial growth not only explains the  
30 formation of the metastable phase but also accounts for the experimental growth direction of the  
31 orthorhombic  $\text{Bi}_2\text{Se}_3$  crystals. The spontaneous formation of a seed layer alleviates the need to use  
32 a single-crystal substrate for electrodeposition, enabling the growth of metastable, orthorhombic  
33  
34  
35  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

1  
2  
3 Bi<sub>2</sub>Se<sub>3</sub> microcrystals for the first time on polycrystalline substrates including gold and fluorine-  
4 doped tin oxide. Our results demonstrate the feasibility of electrodepositing metastable structures  
5 with high crystallinity on polycrystalline substrates by using nanocrystal seeds (rather than a  
6 single-crystal substrate) to induce epitaxy and enforce the desired phase.  
7  
8  
9  
10  
11  
12  
13  
14

## 15 Results and Discussion

16

17 We first electrodeposited Bi<sub>2</sub>Se<sub>3</sub> films on single-crystal silicon substrates with different  
18 orientations and resistivities and characterized the crystalline phase of the resulting films. The  
19 films were grown at a constant applied potential, and the total charge passed between the working  
20 and counter electrodes was varied to control the amount of material deposited (see **Figure S1** for  
21 representative current traces during film deposition). X-ray diffraction (XRD) patterns of Bi<sub>2</sub>Se<sub>3</sub>  
22 films grown at a potential of -0.45 V vs. an Ag/AgCl reference electrode for a total charge density  
23 of 2 C/cm<sup>2</sup> are shown in **Figure 1b**. Using either Si (100) substrates with a resistivity of 4.4 Ω×cm  
24 or Si (111) substrates with a resistivity of 1.3 Ω×cm, we consistently observed that the Bi<sub>2</sub>Se<sub>3</sub> films  
25 grew in the orthorhombic phase at this potential. On the other hand, using Si (111) substrates with  
26 a higher dopant density and a resistivity of 0.0061 Ω×cm, the Bi<sub>2</sub>Se<sub>3</sub> films consistently grew in the  
27 rhombohedral phase at -0.45 V vs. Ag/AgCl. These results show that the phase of the Bi<sub>2</sub>Se<sub>3</sub> films  
28 can be controlled by the resistivity of the substrate.  
29  
30  
31  
32  
33  
34  
35  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60



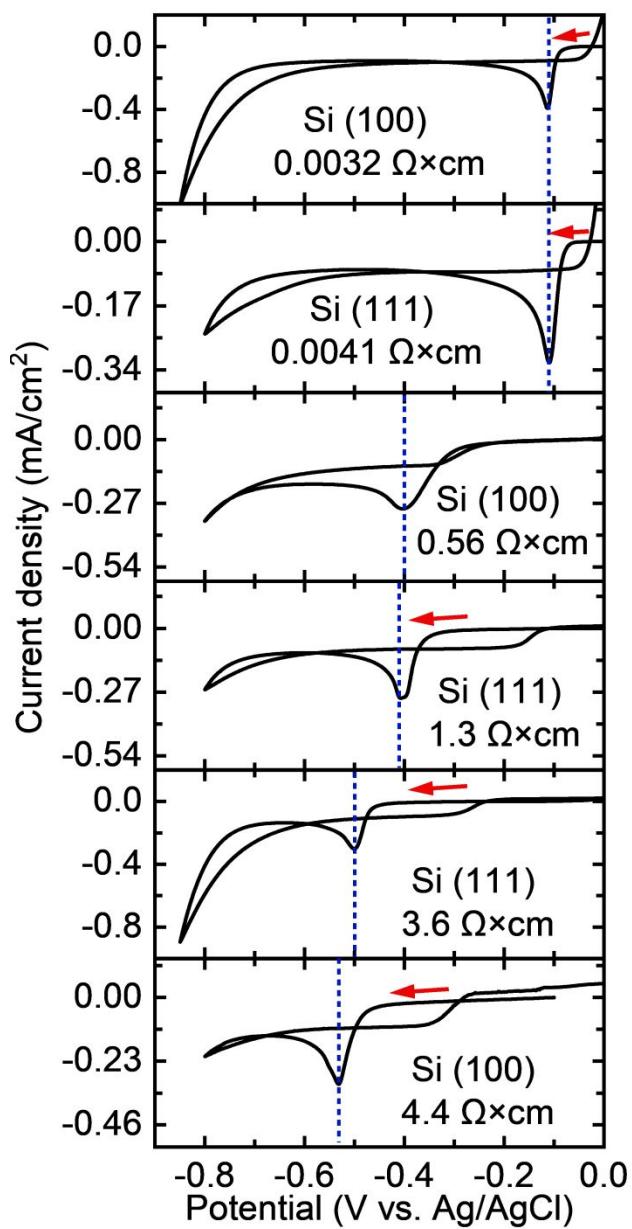
**Figure 1.** Atomic structures of (a) the stable, rhombohedral phase of  $\text{Bi}_2\text{Se}_3$  (collection code #165226,  $R\text{-}\text{Bi}_2\text{Se}_3$ ) and (b) metastable, orthorhombic phase of  $\text{Bi}_2\text{Se}_3$  (collection code #617093,  $O\text{-}\text{Bi}_2\text{Se}_3$ ). The initial structures come from the Inorganic Crystal Structure Database (ICSD)<sup>56</sup> and were relaxed using density-functional theory. (c) Thin-film XRD patterns of  $\text{Bi}_2\text{Se}_3$  films grown on single-crystal Si substrates with different orientations and resistivities. The applied potential used to grow each film was  $-0.45$  V vs.  $\text{Ag}/\text{AgCl}$ , and the total amount of charge passed was  $2$  C/cm<sup>2</sup>. The asterisk marks an impurity, the (111) peak of Ag, which was used to make electrical contact to the Si substrate (see the **Experimental section** for more details on electrode and sample preparation). The top, red pattern is the standard XRD powder pattern of orthorhombic  $\text{Bi}_2\text{Se}_3$  (PDF #04-003-6014), and the bottom, blue pattern is the standard XRD powder pattern of rhombohedral  $\text{Bi}_2\text{Se}_3$  (PDF #04-002-5483). Experimental patterns in red denote growth of  $O\text{-}\text{Bi}_2\text{Se}_3$ , and the pattern in blue denotes  $R\text{-}\text{Bi}_2\text{Se}_3$ .

**Table 1.** Summary of the crystalline phases of  $\text{Bi}_2\text{Se}_3$  films grown via electrodeposition at a constant potential on single-crystal Si substrates with different orientations and resistivities. *O* indicates the orthorhombic phase. *R* indicates the rhombohedral phase. *R/O* indicates the film is a mixture of the rhombohedral and orthorhombic phases. None indicates there was no observable film formation (or that the deposited material fell off the substrate during deposition). Deposition at a potential of -0.48 V vs. Ag/AgCl was only performed on the Si substrates with resistivities of 1.3 and 0.56  $\Omega \times \text{cm}$ . The standard deviation in the resistivity of each Si substrate was determined by measuring four different areas of the same substrate.

Substrate orientation	Substrate resistivity ( $\Omega \times \text{cm}$ )	Phase formed at various potentials (vs. Ag/AgCl)							Reduction peak (V vs. Ag/AgCl) in $\text{Bi}(\text{NO}_3)_3$ solution
		-0.50 V	-0.48 V	-0.45 V	-0.30 V	-0.20 V	-0.10 V	0.00 V	
(100)	4.4 $\pm$ 0.2	None	-	O	O	None	None	None	-0.53
(111)	3.6 $\pm$ 0.1	None	-	O	O	None	None	None	-0.50
(111)	1.3 $\pm$ 0.1	<i>R</i>	<i>R/O</i>	O	O	None	None	None	-0.41
(100)	0.56 $\pm$ 0.01	<i>R</i>	<i>R</i>	<i>R/O</i>	O	None	None	None	-0.40
(111)	0.0041 $\pm$ 0.0003	None	-	<i>R</i>	<i>R</i>	<i>R</i>	O	O	-0.11
(100)	0.0032 $\pm$ 0.0001	None	-	<i>R</i>	<i>R</i>	<i>R</i>	O	O	-0.11

We next varied the applied potential used to grow the  $\text{Bi}_2\text{Se}_3$  films. **Table 1** provides a summary of the phases formed on single-crystal Si substrates with different orientations and resistivities. XRD patterns for each sample listed in **Table 1** are provided in **Figures S2 – S7** of the **Supporting Information**. For Si substrates with the highest resistivities (3.6 and 4.4  $\Omega \times \text{cm}$ ), we could only electrodeposit  $\text{Bi}_2\text{Se}_3$  films within a narrow potential range. Deposition at potentials more negative than -0.45 V vs. Ag/AgCl led to delamination of the film during growth, while no growth was observed at potentials positive of -0.30 V vs. Ag/AgCl. At potentials of -0.30 and -0.45

1  
2  
3 V vs. Ag/AgCl, we observed the metastable, orthorhombic phase (**Figures S6 and S7**). For Si  
4 substrates with lower resistivities, we found that we could control the resulting phase based on the  
5 applied potential. For Si (111) substrates with a resistivity of  $1.3 \Omega \times \text{cm}$ , films grown at -0.30 and  
6 -0.45 V vs. Ag/AgCl exhibited the orthorhombic phase of  $\text{Bi}_2\text{Se}_3$ . At -0.48 V vs. Ag/AgCl, the  
7 films consisted of a mixture of orthorhombic and rhombohedral phases. At -0.50 V, the films  
8 exhibited the rhombohedral phase (**Figure S5**). For orthorhombic  $\text{Bi}_2\text{Se}_3$  films, we did not observe  
9 the formation of any compounds other than  $\text{Bi}_2\text{Se}_3$  by XRD. For rhombohedral  $\text{Bi}_2\text{Se}_3$  films grown  
10 at more negative potentials (-0.45 to -0.50 V), we observed the presence of elemental selenium as  
11 a minor impurity phase (**Figures S3 and S4**). As the resistivity of the Si substrate decreased, the  
12 transition between the two phases shifted to more positive potentials. For Si (100) substrates with  
13 a resistivity of  $0.56 \Omega \times \text{cm}$ , the transition from orthorhombic to rhombohedral phases was between  
14 -0.30 and -0.48 V vs. Ag/AgCl (**Figure S4**). For Si (100) substrates with a resistivity of  
15  $0.0032 \Omega \times \text{cm}$  and Si (111) substrates with a resistivity of  $0.0041 \Omega \times \text{cm}$ , the orthorhombic phase  
16 was observed at potentials of 0.00 and -0.10 V vs. Ag/AgCl. However, films grown at potentials  
17 of -0.20, -0.30, and -0.45 V vs. Ag/AgCl exhibited the rhombohedral phase (**Figures S2 and S3**).  
18 Our results demonstrate that the combination of applied potential and the resistivity of the Si  
19 substrate, rather than its orientation, control the resulting phase of the  $\text{Bi}_2\text{Se}_3$  films. Si substrates  
20 with similar resistivities but different orientations produce the same phase at a given potential.  
21  
22  
23  
24  
25  
26  
27  
28  
29  
30  
31  
32  
33  
34  
35  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

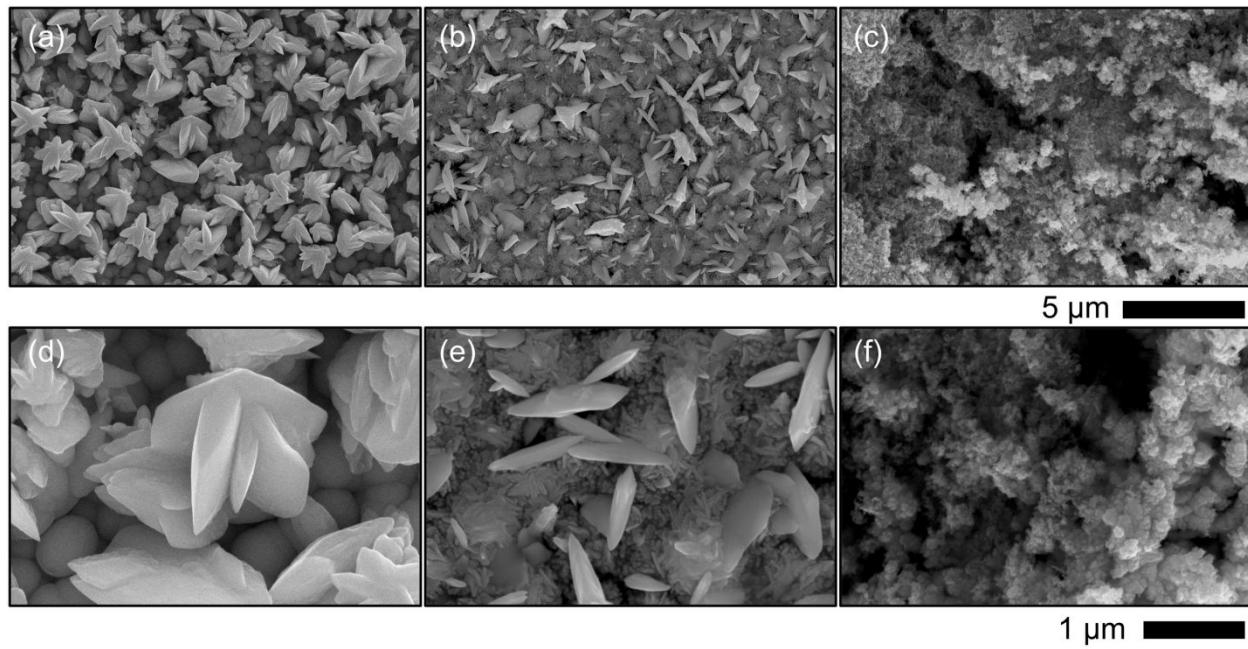


**Figure 2.** Cyclic voltammograms in an aqueous solution of 1 mM  $\text{Bi}(\text{NO}_3)_3$  and 0.5 M  $\text{HNO}_3$  using single-crystal Si electrodes with different orientations and resistivities. Each Si electrode was first swept from the open-circuit potential to 0 V vs.  $\text{Ag}/\text{AgCl}$  (not shown) followed by scanning towards more negative potentials (red arrows). The scan rate was 20 mV/s. The blue dashed lines indicate the positions of the redox wave corresponding to the reduction of  $\text{Bi}^{3+}$  to  $\text{Bi}^0$  during the initial negative sweep, which are listed in **Table 1**.

The resistivity of the Si substrate determines the potential at which Bi is deposited on the electrode and correlates with the resulting phase of the  $\text{Bi}_2\text{Se}_3$  film. We used cyclic voltammetry (CV) to determine the reduction potential of  $\text{Bi}^{3+}$  using Si substrates with different resistivities as the working electrode. The solution used for CV contained  $\text{Bi}(\text{NO}_3)_3$  at the same concentration and pH used to deposit the  $\text{Bi}_2\text{Se}_3$  films (but without  $\text{SeO}_2$ ). The overpotential for the reduction of  $\text{Bi}^{3+}$  increases as the resistivity of the working electrode increases, as shown in **Figure 2**. The peak maxima for the redox wave corresponding to the reduction of  $\text{Bi}^{3+}$  shift to more negative values for Si substrates with higher resistivities.

We find that the  $\text{Bi}_2\text{Se}_3$  films grow in the orthorhombic phase when the applied potential during film growth is close to or positive of the peak potential for  $\text{Bi}^{3+}$  reduction. For example, using an Si (111) substrate with a resistivity of  $1.3 \Omega \times \text{cm}$ , the  $\text{Bi}^{3+}$  reduction peak occurs at  $-0.41 \text{ V}$  vs.  $\text{Ag}/\text{AgCl}$  (see **Figure 2**). The orthorhombic phase is formed at a potential of  $-0.45 \text{ V}$  vs.  $\text{Ag}/\text{AgCl}$ , while the rhombohedral phase is formed at  $-0.50 \text{ V}$  vs.  $\text{Ag}/\text{AgCl}$  (**Figure S5**). For both an Si (100) substrate with a resistivity of  $0.0032 \Omega \times \text{cm}$  and an Si (111) substrate with a resistivity of  $0.0041 \Omega \times \text{cm}$ , the  $\text{Bi}^{3+}$  reduction peak occurs at  $-0.11 \text{ V}$  vs.  $\text{Ag}/\text{AgCl}$ . The orthorhombic phase is formed at potentials of  $0.00$  and  $-0.10 \text{ V}$  vs.  $\text{Ag}/\text{AgCl}$  for both substrates, while the rhombohedral phase occurs at more negative potentials of  $-0.20$ ,  $-0.30$ , and  $-0.45 \text{ V}$  vs.  $\text{Ag}/\text{AgCl}$  (**Figures S2** and **S3**). Thus, when the applied potential is sufficiently more negative than the  $\text{Bi}^{3+}$  reduction peak, the rhombohedral phase is formed. In solutions containing only  $\text{SeO}_2$ , we found that the reduction peak for  $\text{Se}^{4+}$  was approximately  $-0.6 \text{ V}$  vs.  $\text{Ag}/\text{AgCl}$  for all Si substrates as shown in **Figure S8**. As described further below, growing  $\text{Bi}_2\text{Se}_3$  films at a potential close to or positive of the reduction

peak for  $\text{Bi}^{3+}$  leads to a Bi-rich film during the early stages of growth, which is observed for all films having the orthorhombic phase.



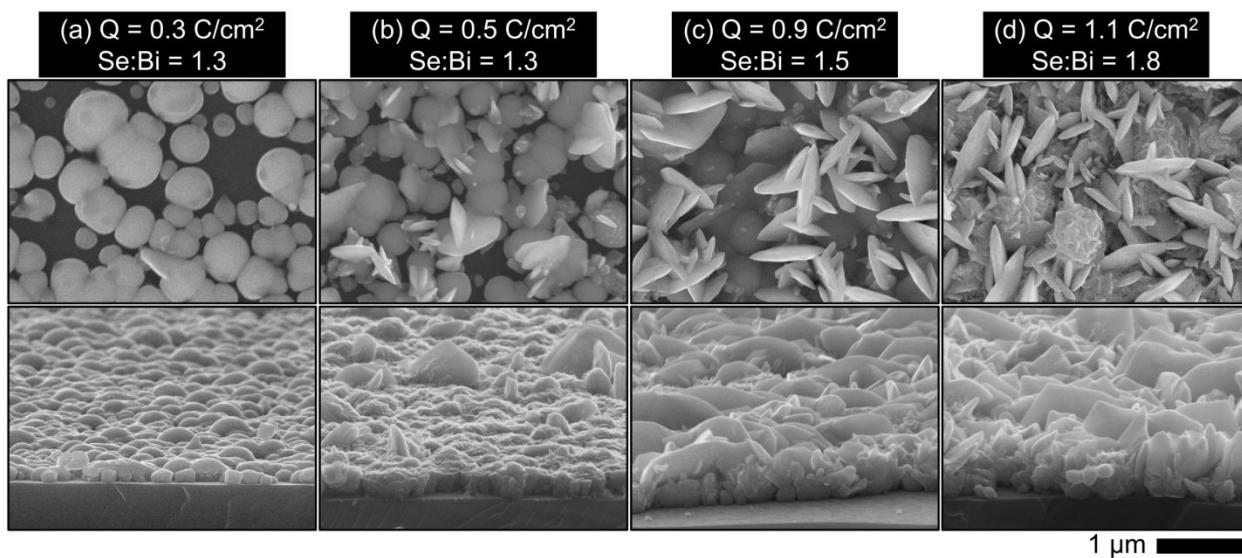
**Figure 3.** SEM images of  $\text{Bi}_2\text{Se}_3$  films grown on single-crystal Si substrates with different orientations and resistivities. (a, d) Low- and high-magnification SEM images of a  $\text{Bi}_2\text{Se}_3$  film grown on a Si (111) electrode with a resistivity of  $1.3 \Omega \times \text{cm}$  at a potential of  $-0.30 \text{ V}$  vs. Ag/AgCl for a total charge density of  $2 \text{ C}/\text{cm}^2$ . These conditions produce films with the orthorhombic phase as measured by XRD (see **Figure S5**). (b, e) SEM images of a  $\text{Bi}_2\text{Se}_3$  film grown on a Si (100) electrode with a resistivity of  $0.0032 \Omega \times \text{cm}$  at a potential of  $-0.10 \text{ V}$  vs. Ag/AgCl for a total charge density of  $2 \text{ C}/\text{cm}^2$ . These conditions produce films with the orthorhombic phase (see **Figure S2**). (c, f) SEM images of a  $\text{Bi}_2\text{Se}_3$  film grown on a Si (100) electrode with a resistivity of  $0.0032 \Omega \times \text{cm}$  at a potential of  $-0.30 \text{ V}$  vs. Ag/AgCl for a total charge density of  $2 \text{ C}/\text{cm}^2$ . These conditions produce films with the rhombohedral phase (see **Figure S2**). The scale bars of  $5 \mu\text{m}$  and  $1 \mu\text{m}$  apply to the top row and bottom row of images, respectively.

1  
2  
3  
4  
5 Bi<sub>2</sub>Se<sub>3</sub> films with the orthorhombic phase possess larger crystallite sizes than those with the  
6 rhombohedral phase. **Figure 3** shows representative scanning electron microscopy (SEM) images  
7 of films grown on different single-crystal Si substrates. Films with the orthorhombic phase consist  
8 of interleaved platelets with microscale dimensions, as shown in **Figure 3a, d**. These platelets  
9 grow out of a dense layer of hemispherical seed particles that can be seen underneath the platelets  
10 in **Figure 3a, d** (see also **Figure S9**). The platelet morphology is observed for orthorhombic Bi<sub>2</sub>Se<sub>3</sub>  
11 films grown on both Si (111) (**Figure 3a, d**) and Si (100) substrates (**Figure 3b, e**), which  
12 reinforces that epitaxy with the Si (100) surface is not necessary to produce the orthorhombic phase.  
13 In sharp contrast, films with the rhombohedral phase consist of aggregated nanoscale crystallites  
14 (**Figure 3c, f** and **Figure S10**). Consistent with the SEM images, XRD patterns show broader  
15 peaks for films with the rhombohedral phase compared to the orthorhombic phase (see **Figure 1b**  
16 and **Figures S2 – S5**). Furthermore, the relative intensities of peaks in the thin-film XRD patterns  
17 for the orthorhombic phase show texture effects indicating that the crystals have a preferred  
18 orientation. Notably, the (020) peak at 44° shows a higher relative intensity compared to the  
19 standard powder pattern (**Figure 1c**). While the (112) peak at 27.6° also shows a higher relative  
20 intensity, we found that the intensity of this peak varies for different entries of orthorhombic Bi<sub>2</sub>Se<sub>3</sub>  
21 in the ICSD.  
22  
23

24 The morphological evolution of Bi<sub>2</sub>Se<sub>3</sub> films with the orthorhombic phase, as characterized  
25 using SEM imaging, is shown in **Figure 4**. These samples were grown on Si (111) substrates with  
26 a resistivity of 3.6 Ω×cm at a potential of -0.45 V vs. Ag/AgCl for different amounts of charge  
27 passed. For a charge density of 0.3 C/cm<sup>2</sup>, the film consists of a layer of sub-micron-sized  
28 hemispherical seeds that cover the Si substrate (with some exposed regions of the substrate as  
29  
30  
31  
32  
33  
34  
35  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

1  
2  
3 shown in the top-down SEM image in **Figure 4a**). At this stage of growth, the seeds have an  
4 elemental Se:Bi ratio of 1.3 as determined by energy dispersive x-ray (EDX) spectroscopy. The  
5 seeds are rich in bismuth relative to the Se:Bi ratio of 1.5 in  $\text{Bi}_2\text{Se}_3$ . Thin-film XRD patterns do  
6 not show any distinct diffraction peaks at this stage of growth, indicating the initial seed layer has  
7 low crystallinity (see **Figure S9**). For a charge density of  $0.5 \text{ C/cm}^2$ , the Se:Bi ratio is still 1.3, but  
8 platelet crystallites have nucleated from the hemispherical seeds (**Figure 4b**). The platelets  
9 continue to grow with the amount of charge passed; the platelets also branch, and new platelets  
10 nucleate from the seed layer. The films have the expected Se:Bi ratio of 1.5 for a charge density  
11 of  $0.9 \text{ C/cm}^2$  (**Figure 4c**). However, the films eventually become rich in Se with an elemental  
12 Se:Bi ratio of 1.8 at a charge density of  $1.1 \text{ C/cm}^2$  (**Figure 4d**). The excess Se relative to the ratio  
13 for  $\text{Bi}_2\text{Se}_3$  indicates the co-deposition of elemental selenium, which is supported by x-ray  
14 photoelectron spectroscopy (XPS) (see **Figure S12**). Films grown on other Si substrates at  
15 potentials that produce the orthorhombic phase exhibit a similar evolution in their morphology.  
16  
17

18 Films possessing the rhombohedral phase undergo a very different growth pattern. Unlike the  
19 growth of the orthorhombic phase, there is no seed layer at the early stages of growth. Aggregated  
20 nanoscale crystallites form directly on the Si electrode. The aggregates become denser until they  
21 cover the Si substrate and continue to grow out from the surface of the electrode with increasing  
22 deposition times (see **Figure S10**). Unlike the orthorhombic films, films with the rhombohedral  
23 phase are rich in selenium relative to the stoichiometry of  $\text{Bi}_2\text{Se}_3$  at all stages of growth (**Figures**  
24 **S10** and **14b**).  
25  
26  
27  
28  
29  
30  
31  
32  
33  
34  
35  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

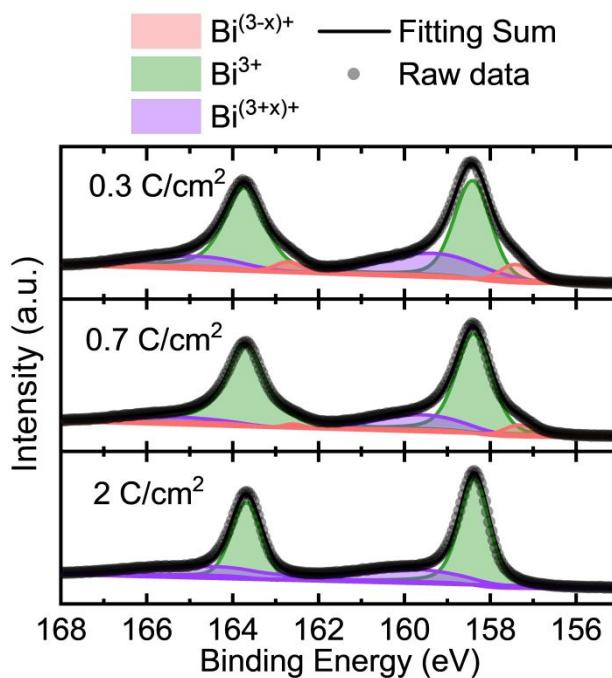


**Figure 4.** SEM images of Bi<sub>2</sub>Se<sub>3</sub> films grown on Si (111) electrodes with a resistivity of 3.6 Ω×cm at a potential of -0.45 V vs. Ag/AgCl for total charge densities of (a) 0.3 C/cm<sup>2</sup>; (b) 0.5 C/cm<sup>2</sup>; (c) 0.9 C/cm<sup>2</sup>; (d) 1.1 C/cm<sup>2</sup>. These growth conditions produce films with the orthorhombic phase as determined by XRD (see **Figure S6**). For each sample, a top-down image is shown in the top row, and a cross-sectional image is shown in the bottom row. The scale of 1 μm applies to all images.

The essential difference between formation of the orthorhombic and rhombohedral phases appears to be the amorphous seed layer that forms during the initial stage of growth for the orthorhombic phase. To characterize the seed layer, we next conducted XPS of Bi<sub>2</sub>Se<sub>3</sub> films grown on Si (100) electrodes with a resistivity of 4.4 Ω×cm, which is a representative case that results in the growth of the orthorhombic phase as determined by XRD (see **Figure S7**). The films were first sputtered to remove the surface oxide layer that forms over time when the samples are left out in air (**Figure S11**). By fitting the peaks in the binding region of Bi 4f<sub>5/2</sub> and 4f<sub>7/2</sub> electrons, we observe varying contributions from Bi<sup>3+</sup> as well as Bi in both lower and higher oxidation states in films grown for different amounts of time (**Figure 5**). The most prominent contribution for all

1  
2  
3 films is  $\text{Bi}^{3+}$ , consistent with the formation of  $\text{Bi}_2\text{Se}_3$ .<sup>57</sup> The weak peaks at higher binding energies,  
4 labeled  $\text{Bi}^{(3+x)+}$ , that are observed at all deposition times could arise from either  $\text{Bi}^{5+}$  or  $\text{Bi}^{3+}$  bonded  
5 to residual oxygen (see **Supporting Discussion S1** in the **SI** for further details).<sup>55, 57-58</sup> There are  
6 also minor peaks from Bi in a lower oxidation state, labeled as  $\text{Bi}^{(3-x)+}$ ,<sup>59-61</sup> which are most  
7 prominent for the earliest stage of growth ( $0.3 \text{ C}/\text{cm}^2$ ) measured, but disappear by the final stage  
8 ( $2 \text{ C}/\text{cm}^2$ ). Bader charge analysis of a series of bismuth selenide and oxide compounds is consistent  
9 with these assignments (see **Supporting Discussion S1**, **Table S4**, and **Figure S15**). We observe  
10 the contribution from  $\text{Bi}^{(3-x)+}$  in films that exhibit the orthorhombic phase on other Si substrates,  
11 as well as the decrease in its contribution with growth time (**Figure S13a**). On the other hand,  
12 while films with the rhombohedral phase show a minor contribution from  $\text{Bi}^{(3-x)+}$  at later stages of  
13 growth, this oxidation state does not appear during the early stages of growth (**Figure S14a**).  
14  
15

16 Comparing XPS in **Figure 5** to the SEM images in **Figure 4**, when the amorphous, Bi-rich  
17 seed layer is formed during the early stages of deposition (i.e.,  $0.3$  and  $0.5 \text{ C}/\text{cm}^2$  of charge passed),  
18 the films contain Bi in a lower oxidation state (in addition to the  $\text{Bi}^{3+}$  and  $\text{Bi}^{(3+x)+}$  states). As the  
19 orthorhombic crystallites nucleate and grow from the seed layer, the overall composition becomes  
20 closer to  $\text{Bi}_2\text{Se}_3$  matching the orthorhombic phase observed by XRD. XPS in the region of Se  $3d$   
21 states shows that the co-deposition of Se metal leads to Se-rich films relative to  $\text{Bi}_2\text{Se}_3$  (i.e., Se:Bi  
22  $> 1.5$ ) during the final stages of growth (see **Figure S12**). The combined characterization by XRD,  
23 EDX spectroscopy, SEM, and XPS, point towards the formation of an intermediate bismuth  
24 selenide compound during the early stages of growth with a distinct structure and composition  
25 from that of  $\text{Bi}_2\text{Se}_3$  that induces formation of the metastable orthorhombic phase of  $\text{Bi}_2\text{Se}_3$ .  
26  
27  
28  
29  
30  
31  
32  
33  
34  
35  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

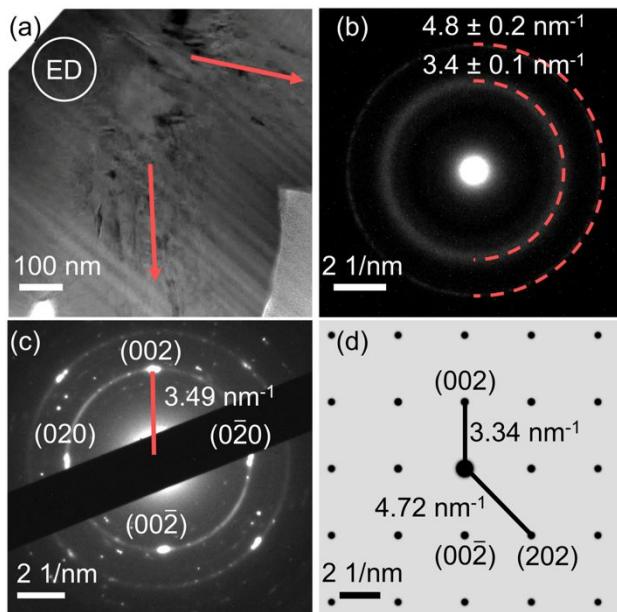


**Figure 5.** XPS of  $\text{Bi}_2\text{Se}_3$  films showing the binding energy region for Bi 4f electrons. The films were grown on Si (100) substrates with a resistivity of  $4.4 \Omega \times \text{cm}$  at a potential of -0.45 V vs. Ag/AgCl for different charge densities. These growth conditions produce films with the orthorhombic phase (see **Figure S7**). The shaded regions show the deconvolution of the peaks into contributions from  $\text{Bi}^{(3+x)+}$  (purple),  $\text{Bi}^{3+}$  (green), and  $\text{Bi}^{(3-x)+}$  (light red). The gray points show the raw data, and the black lines show the sum of fitting the peaks to the different oxidation states of Bi.

We used transmission electron microscopy (TEM) to gain further insights into the structure of the seed layer that produces orthorhombic  $\text{Bi}_2\text{Se}_3$  crystals. A cross-sectional, bright-field image of the interfacial region between the seed layer and two orthorhombic crystallites that share a twin boundary is shown in **Figure 6a**. An electron diffraction pattern of the seed layer (indicated by the white circle in **Figure 6a**) is shown in **Figure 6b**. The pattern shows two relatively sharp rings,

which indicates the likely presence of randomly oriented nanocrystals within the amorphous seed layer.<sup>62</sup> We find the radius of the inner ring to be  $3.4 \pm 0.1 \text{ nm}^{-1}$  and that of the outer ring to be  $4.8 \pm 0.2 \text{ nm}^{-1}$ , which provide the nearest and second-nearest neighbor distances between atoms in the nanocrystals. Furthermore, we observed several nanocrystals embedded within the amorphous seed layer in a dark-field TEM image shown in **Figure S18b**—that was obtained using a diffracted beam from an adjacent  $\text{Bi}_2\text{Se}_3$  crystallite. To further characterize the structure of the nanocrystals within the seed region, we performed electron diffraction on a film where the deposition was terminated at the formation of the seed layer (i.e., before nucleation of the orthorhombic crystallites). For this sample, the seed layer was scraped off from the Si substrate and transferred to a TEM grid. The electron diffraction pattern of the sample at this stage of growth is shown in **Figure 6c**. The pattern shows four main spots in the inner ring with 4-fold symmetry and a reciprocal spacing of  $3.49 \text{ nm}^{-1}$  that matches the spacing of the inner ring in the cross-sectional sample. To identify the structure of these nanocrystals, we searched for all experimentally reported compounds of Bi and Se in the ICSD (see **Table S5**) and simulated their diffraction patterns to compare them to our experimental pattern. We find that BiSe with the rock salt structure ( $Fm\bar{3}m$ ) provides the best match. An atomic model of cubic BiSe is shown in **Figure S16**. A simulated electron diffraction pattern along the [100] zone axis for the structure obtained from the ICSD is shown in **Figure 6d**. We find the reciprocal lattice spacings of the (002) and (202) planes are  $3.34 \text{ nm}^{-1}$  and  $4.72 \text{ nm}^{-1}$ , respectively, which match well with the spacings of the 1<sup>st</sup> and 2<sup>nd</sup> rings in the experimental pattern in **Figure 6b**. Among the compounds searched, the only other structure that possesses a four-fold symmetry is  $\text{Bi}_2\text{Se}_3$  with the  $\text{Zn}_3\text{P}_2$  structure ( $P4_2/nmc$ ). However, its simulated diffraction pattern does not match the experimental lattice spacings, as shown in **Figure S17**. Based on the good agreement between the simulated and experimental diffraction patterns

and the nanocrystals with bright contrast in the dark-field image (**Figure S18b**), we propose the intermediate Bi–Se compound, critical for the formation of the orthorhombic phase, consists of nanocrystals of cubic BiSe nanocrystals embedded within a Bi-rich, amorphous seed layer that initially deposits on the Si electrode. This hypothesis is consistent with the lower Se:Bi ratio observed for the seed region using EDX spectroscopy (**Figure 4a**). Furthermore, Bader charge analysis of BiSe indicates that it is responsible for the  $\text{Bi}^{(3-x)+}$  peaks observed in XPS during the early stages of growth (see **Supporting Discussion S1, Table S4**, and **Figure S15**).



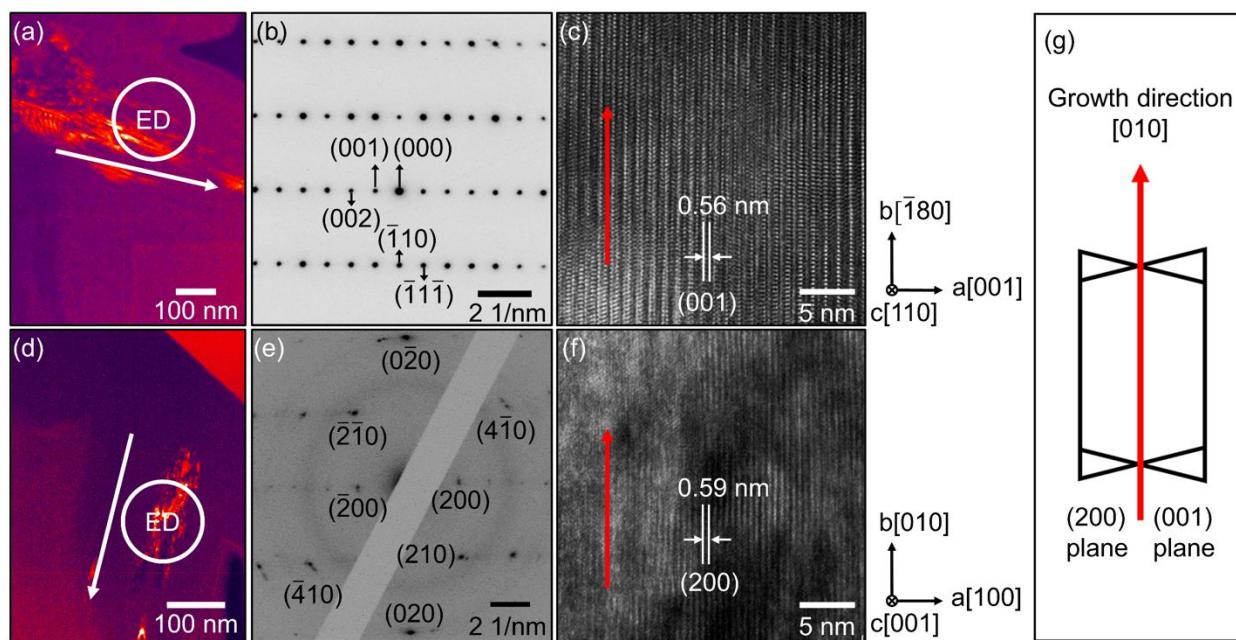
**Figure 6.** (a) Cross-sectional, bright-field TEM image of an orthorhombic  $\text{Bi}_2\text{Se}_3$  film grown on a Si (111) electrode with a resistivity of  $1.3 \Omega \times \text{cm}$  at a potential of  $-0.30 \text{ V}$  vs.  $\text{Ag}/\text{AgCl}$  for a charge density of  $0.9 \text{ C}/\text{cm}^2$ . The red arrows indicate the growth directions of the two crystallites separated by a twin boundary. (b) Electron diffraction pattern of a region on the same film near the interface with the Si growth substrate. The white circle in panel (a) indicates the area used to obtain the electron diffraction pattern of the cross section shown in (b). (c) Electron diffraction pattern of a

1  
2  
3 separate sample grown on a Si (111) electrode with a resistivity of  $0.0061 \Omega \times \text{cm}$  at a potential of  
4  
5 -0.10 V vs. Ag/AgCl for a charge density of  $0.2 \text{ C}/\text{cm}^2$ . To obtain the electron diffraction pattern,  
6  
7 the film was scraped off the Si substrate and transferred to a TEM grid. (d) Simulated electron  
8  
9 diffraction pattern of cubic BiSe along the [100] zone axis.  
10  
11  
12  
13  
14

15 Having established the structure of the seed region, we next characterized the growth directions  
16 of the twinned orthorhombic  $\text{Bi}_2\text{Se}_3$  crystals that nucleate from the seed region, as shown in **Figure**  
17  
18 7. Dark-field TEM images of the two adjacent orthorhombic  $\text{Bi}_2\text{Se}_3$  crystallites are shown in  
19  
20 **Figure 7a** and **d**. Electron diffraction patterns of each crystallite were obtained by tilting the  
21  
22 respective grains so that they are oriented along the [110] and [001] zone axes, respectively, as  
23  
24 shown in **Figure 7b** and **e**. High-resolution TEM images of the two grains that are oriented along  
25  
26 the [110] and [001] zone axes are shown in **Figure 7c** and **f**, respectively. From the lattice spacings,  
27  
28 we derived the lattice planes in the corresponding images to be (001) and (200), respectively. We  
29  
30 find the growth direction of the two crystallites to be along the [010] axis (red arrows in **Figure**  
31  
32 **7c** and **f**) from the intersection between the (001) and (200) planes, as shown schematically in  
33  
34 **Figure 7g**.  
35  
36

37 The formation of such oriented crystallites can occur through two scenarios: (I) if the (010)  
38  
39 surface of orthorhombic  $\text{Bi}_2\text{Se}_3$  has a significantly lower energy than the other surfaces; or (II) if  
40  
41 there is epitaxy between the orthorhombic  $\text{Bi}_2\text{Se}_3$  crystallites and the BiSe nanocrystals embedded  
42  
43 in the seed layer. We used density-functional theory (DFT) to calculate the surface energies of  
44  
45 various low-index surfaces of  $\text{Bi}_2\text{Se}_3$  in the orthorhombic and rhombohedral phases as well as  
46  
47 cubic BiSe. We find that the (010) surface of orthorhombic  $\text{Bi}_2\text{Se}_3$  has the highest surface energy  
48  
49 compared to the (100) and (001) surfaces, as shown in **Table S6**. We can therefore rule out scenario  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

I. In support of scenario II, we obtained an electron diffraction pattern from a region at the intersection of the two orthorhombic  $\text{Bi}_2\text{Se}_3$  crystallites, shown in **Figure S18**. We find that the two grains share a twin boundary at the  $(1\bar{1}5)$  plane. The lattice parameters along the [100] and [001] directions of orthorhombic  $\text{Bi}_2\text{Se}_3$  are similar (11.66 Å and 11.45 Å). So, in some cases, the  $\text{Bi}_2\text{Se}_3$  lattice can deform along [100] to match with the cubic symmetry of underlying  $\text{BiSe}$ , while in other cases, it can deform along [001]. When these different crystallites grow to merge, they can result in the formation of a twin boundary, as we observe experimentally. Thus, the presence of oriented and twinned crystallites of orthorhombic  $\text{Bi}_2\text{Se}_3$  suggest that the nucleation and growth of  $\text{Bi}_2\text{Se}_3$  occurs epitaxially from the cubic  $\text{BiSe}$  nanocrystals in the seed layer.



**Figure 7.** Cross-sectional TEM images and electron diffraction patterns of the twinned orthorhombic  $\text{Bi}_2\text{Se}_3$  crystallites that grew from the seed region shown in **Figure 6a**. (a, d) Dark-field cross-sectional TEM images of the two orthorhombic  $\text{Bi}_2\text{Se}_3$  crystallites. The white circles in panels (a) and (d) indicate the selected areas used to obtain electron diffraction patterns shown in

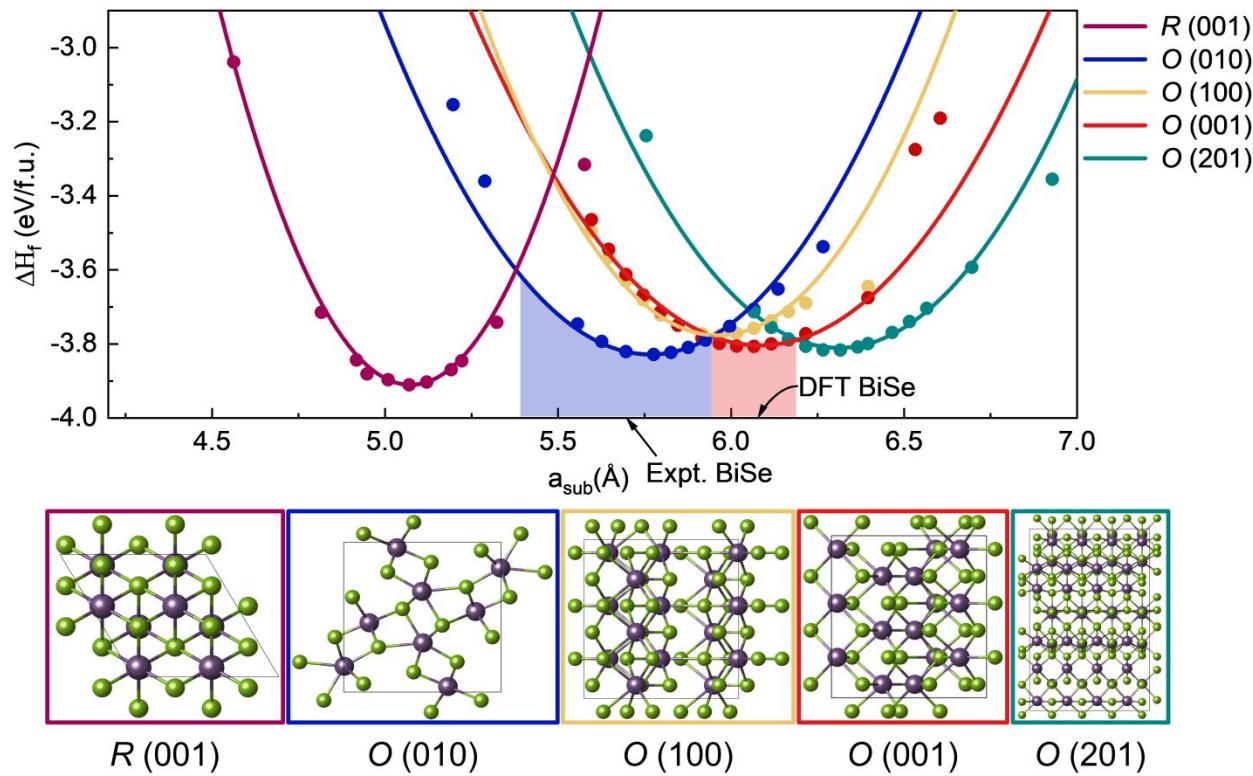
1  
2  
3 panels (b) and (e) and high-resolution TEM images in panels (c) and (f), respectively. The white  
4 arrows indicate the growth direction of each crystallite. (b, e) Electron diffraction patterns for the  
5 two orthorhombic  $\text{Bi}_2\text{Se}_3$  crystallites. (c, f) High-resolution bright-field TEM images of the two  
6 orthorhombic  $\text{Bi}_2\text{Se}_3$  crystallites showing (001) and (200) lattice planes that are parallel to the  
7 growth directions of the crystallites, which point upward (red arrows). (g) A schematic showing  
8 the growth of the two twinned crystallites along with their growth direction.  
9  
10  
11  
12  
13  
14  
15  
16  
17  
18

19 We next used DFT calculations to identify the preferred epitaxial relationship between cubic  
20  $\text{BiSe}$  and both orthorhombic and rhombohedral  $\text{Bi}_2\text{Se}_3$  along with the energy of the two phases  
21 under varying epitaxial strains. From the calculated surface energy of the common facets of cubic  
22  $\text{BiSe}$ , and orthorhombic and rhombohedral  $\text{Bi}_2\text{Se}_3$ , which are shown in **Table S6**, we find that the  
23 (001) surface of  $\text{BiSe}$  has the lowest energy followed by the (110) and (111) surfaces, respectively.  
24 Hence, we modeled the growth of  $\text{Bi}_2\text{Se}_3$  on the (001) and (110) surfaces of  $\text{BiSe}$ . We discuss the  
25 results on the (001) surface below and present the results on the (110) surface in the **Supporting**  
26 **Information Figure S20**. For rhombohedral  $\text{Bi}_2\text{Se}_3$ , which has a layered structure, the (001)  
27 surface has a surface energy that is significantly smaller than the other facets due to the weak  
28 interlayer bonding along [001]. Hence, we expect it to serve as the growth plane for rhombohedral  
29  $\text{Bi}_2\text{Se}_3$ . We next built coincident site lattice models between the (001) plane of  $\text{BiSe}$  and the (001)  
30 plane of rhombohedral  $\text{Bi}_2\text{Se}_3$ , as shown in **Figure S19**. According to coincident site lattice theory,  
31 epitaxial interfaces are formed by constraining the film to match the substrate along special  
32 orientations where the lattice sites of the film and the substrate coincide.<sup>21, 26, 63</sup> We tried two  
33 different orientations for the rhombohedral  $\text{Bi}_2\text{Se}_3$  (001) surface on top of the  $\text{BiSe}$  (001) surface,  
34 as shown in **Figure S19**. We further varied the lattice parameter of  $\text{BiSe}$  (001) to account for the  
35  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

1  
2  
3 uncertainty in the lattice parameter of the BiSe nanocrystals — that may arise from their extremely  
4 small size and variable composition, which are challenging to be characterized accurately — and  
5 accordingly varied the epitaxial strain on  $\text{Bi}_2\text{Se}_3$  (see the **Calculation methods** in the  
6 **Experimental section** for more details). The stabilities of orthorhombic and rhombohedral  $\text{Bi}_2\text{Se}_3$   
7 with different orientations and epitaxially matched to BiSe (001) are shown in **Figure 8**. We find  
8 that the model having the [100] direction of rhombohedral  $\text{Bi}_2\text{Se}_3$  orientated along the [001]  
9 direction of BiSe minimizes the epitaxial strain. However, even for this configuration,  
10 rhombohedral  $\text{Bi}_2\text{Se}_3$  experiences a tensile strain of 19% to match the BiSe (001) surface, when  
11 using the theoretical lattice parameters for both the phases. These results suggest that  
12 rhombohedral  $\text{Bi}_2\text{Se}_3$  is unlikely to be epitaxially stabilized on BiSe.  
13  
14

15 We next built coincident site lattice models between the (010), (100), (001), and (201) surfaces  
16 of orthorhombic  $\text{Bi}_2\text{Se}_3$  — that have surface energies ranging between 20.1 – 48 meV/ $\text{\AA}^2$ , as listed  
17 in **Table S6** — and (001) BiSe, as shown in **Figure S19**. We applied biaxial strain to orthorhombic  
18  $\text{Bi}_2\text{Se}_3$  along the two axes of the surfaces shown in the atomic models in **Figure 8**. For the (010)  
19 surface of orthorhombic  $\text{Bi}_2\text{Se}_3$  to match with the BiSe (001) surface, the lengths along the [100]  
20 and [001] axes of  $\text{Bi}_2\text{Se}_3$  were adjusted to be 2 times the lattice parameter of the BiSe substrate, as  
21 shown in **Figure S19** and described in the **Calculation methods**. We then uniformly varied the  
22 lattice parameter of BiSe around its minima to simulate a range of epitaxial strains on the  $\text{Bi}_2\text{Se}_3$   
23 film. This changes the strain along the [100] and [001] axes of the orthorhombic  $\text{Bi}_2\text{Se}_3$  (010)  
24 surface according to the relationship discussed above. The formation enthalpy of (010)  $\text{Bi}_2\text{Se}_3$  as  
25 a function of strain for epitaxy on BiSe (001) is shown in **Figure 8**. We have followed a similar  
26 procedure to calculate the formation enthalpies of orthorhombic  $\text{Bi}_2\text{Se}_3$  with (100), (001), and (201)  
27 surfaces as the growth plane that are epitaxially matched with BiSe (001) for varying epitaxial  
28 strains.  
29  
30  
31  
32  
33  
34  
35  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

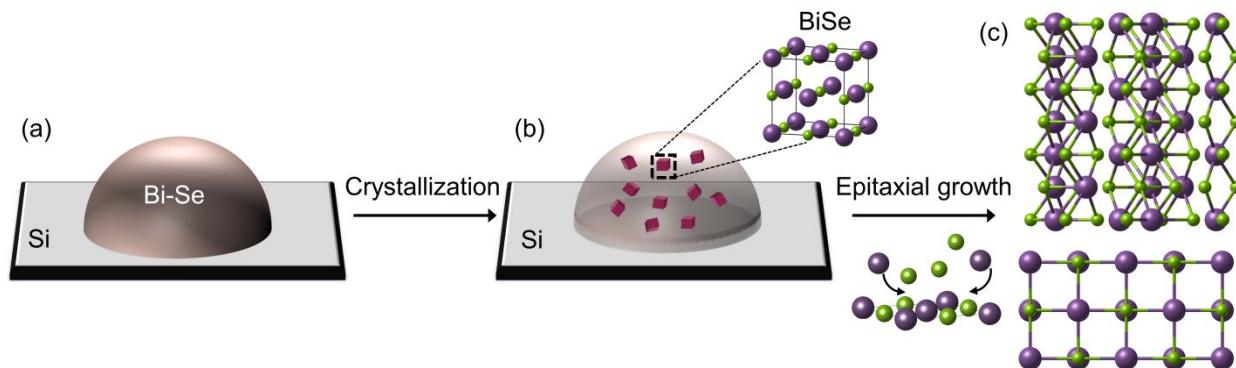
strains, and the results are also shown in **Figure 8**. We find that the orthorhombic  $\text{Bi}_2\text{Se}_3$  phase with (010) growth surface has the lowest formation enthalpy as the substrate lattice parameter varies from 5.40 Å to 5.94 Å. When the BiSe lattice parameter varies from 5.94 Å to 6.19 Å, the orthorhombic  $\text{Bi}_2\text{Se}_3$  phase with (001) surface has the lowest formation energy. The experimental reciprocal spacing of cubic BiSe (002) planes is 3.49 nm<sup>-1</sup>, which corresponds to a unit cell length of 5.73 Å for BiSe. For a BiSe substrate lattice parameter,  $a_{\text{sub}} = 5.73$  Å, orthorhombic  $\text{Bi}_2\text{Se}_3$  with the (010) growth surface has the lowest formation enthalpy, which agrees with the experimentally observed phase and growth direction using TEM. Overall, our calculations show that for a large range of lattice parameters of BiSe, the orthorhombic phase of  $\text{Bi}_2\text{Se}_3$  can be stabilized over the rhombohedral phase through epitaxy, and the preferred growth direction of the orthorhombic phase is [010] when it grows on the BiSe (001) surface.



**Figure 8.** (Top panel) Change in formation enthalpy of rhombohedral and orthorhombic  $\text{Bi}_2\text{Se}_3$  vs. substrate lattice parameter for various epitaxial relations with the cubic BiSe (001) surface. Low-index surfaces have been considered for epitaxy on BiSe, including the (001) surface of rhombohedral  $\text{Bi}_2\text{Se}_3$ , and the (010), (100), (001), and (201) surfaces of orthorhombic  $\text{Bi}_2\text{Se}_3$  (bottom panel). The experimental and DFT-calculated lattice parameters of the cubic BiSe substrate are 5.73 Å (obtained from **Figure 6b**) and 6.07 Å, respectively, which are marked with black arrows. The blue and red shaded areas indicate the regions where orthorhombic  $\text{Bi}_2\text{Se}_3$  with the (010) and (001) surfaces have the lowest formation energy, respectively. The corresponding atomic structures of the various growth surfaces are shown in the bottom panel.

Based upon our combined experimental and computational results, we propose the following mechanism for the formation of metastable orthorhombic  $\text{Bi}_2\text{Se}_3$ , which is depicted using a schema in **Figure 9**. During the initial stage of growth, the electrochemical potential drives the deposition of hemispherical microscale particles of bismuth and selenium that are amorphous. TEM imaging reveals that cubic BiSe nanocrystals precipitate within this amorphous seed layer. The initial seed layer is rich in Bi relative to the stoichiometry of  $\text{Bi}_2\text{Se}_3$  (see **Figure 4**), but the films become richer in Se over time. As the stoichiometry of the film approaches that of  $\text{Bi}_2\text{Se}_3$ , crystallites of  $\text{Bi}_2\text{Se}_3$  nucleate from the seed layer. DFT calculations indicate that the better epitaxial match between cubic BiSe and orthorhombic  $\text{Bi}_2\text{Se}_3$  stabilizes the metastable phase. The orthorhombic  $\text{Bi}_2\text{Se}_3$  crystallites continue to grow along the [010] direction to form platelet crystals. The occurrence of twin boundaries — that are low energy interfaces — between the different  $\text{Bi}_2\text{Se}_3$  crystallites, as observed in our TEM experiments, results in the formation of interleaved platelets as observed by SEM (**Figures 3, 4**). This mechanism is consistent with all our experimental

1  
2  
3 observations as well as with previous reports of the conditions needed to electrodeposit  
4 orthorhombic  $\text{Bi}_2\text{Se}_3$ .<sup>23, 25</sup>  
5  
6  
7  
8  
9  
10  
11  
12  
13  
14



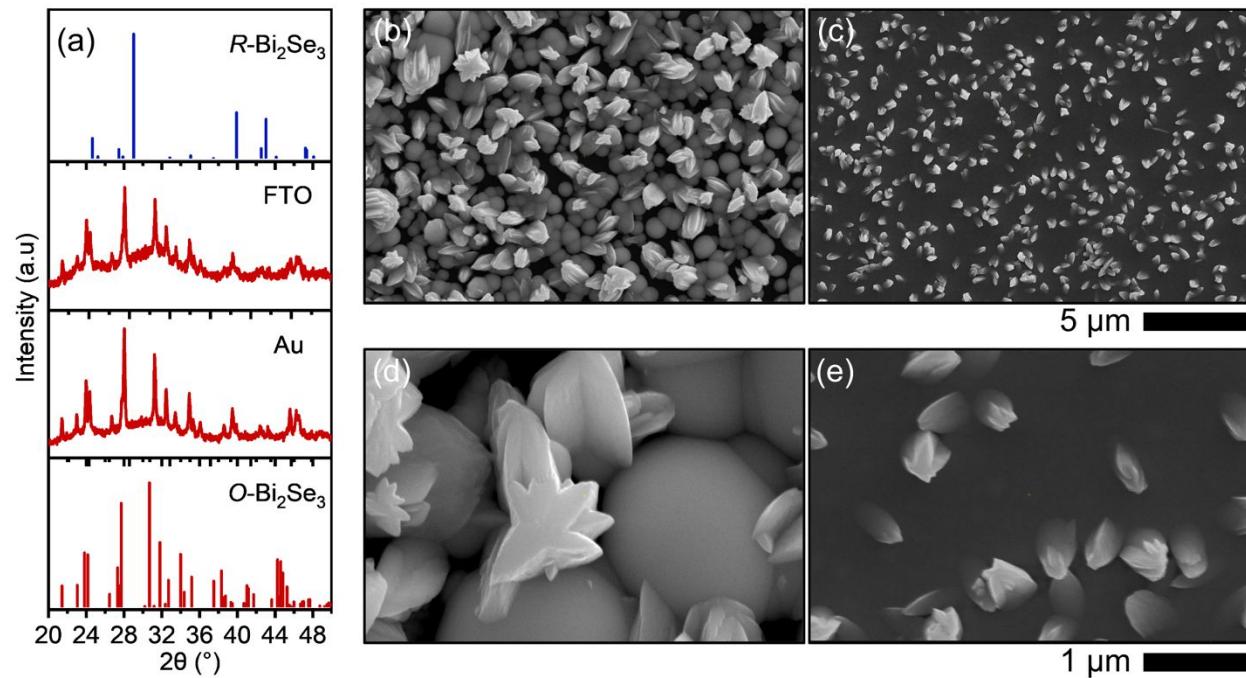
23 **Figure 9.** Schematic of the growth mechanism of metastable, orthorhombic  $\text{Bi}_2\text{Se}_3$ . (a) A Bi-rich,  
24 amorphous seed layer of Bi and Se initially deposits on the Si substrate. (b) Nanocrystals of cubic  
25 BiSe nucleate within the seed layer. (c) As the composition of the film becomes richer in Se,  
26 epitaxy between cubic BiSe and orthorhombic  $\text{Bi}_2\text{Se}_3$  leads to the nucleation and growth of the  
27 metastable phase.  
28  
29  
30  
31  
32  
33  
34  
35  
36

37 The formation of rock salt BiSe is uncommon. While we could only find one report of growing  
38 pure rock salt BiSe,<sup>64</sup> as a structural motif rock salt BiSe is also found in layered superstructures  
39 such as  $[(\text{BiSe})_{1+\delta}]_m[\text{TiSe}_2]_m$ .<sup>65-66</sup> Thus, the question arises as to why this compound forms during  
40 the early stages of electrodeposition. The applied potential used to grow all  $\text{Bi}_2\text{Se}_3$  films with the  
41 orthorhombic phase was positive of the potential needed to deposit Se directly on the Si substrate  
42 (**Figure S8**), such that only Bi is initially deposited. The deposition of Bi on the Si substrate then  
43 reduces the overpotential needed to deposit Se.<sup>23</sup> The reduction of  $\text{Bi}(\text{NO}_3)_3$  and the lower Se:Bi  
44 ratio initially favor formation of a bismuth selenide compound in which Bi is in a lower oxidation  
45 state, such as BiSe. The increase in Se:Bi ratio with deposition time can then promote formation  
46 of the orthorhombic phase.  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

1  
2  
3 of a compound in which Bi is in a higher oxidation state (i.e.,  $\text{Bi}_2\text{Se}_3$ ). Furthermore, the rock salt  
4 structure of BiSe is thermodynamically less stable compared to its trigonal phase. Our calculations  
5 indicate that the rock salt phase is stabilized over the trigonal phase for small crystal sizes (i.e., <  
6 1.5 nm) due to the lower surface energies of the facets that make up the BiSe crystals (see  
7 **Supporting Discussion S4, Table S7, and Figure S21d**).  
8  
9

10 To demonstrate the generality of this seeded growth mechanism, we electrodeposited  
11 orthorhombic  $\text{Bi}_2\text{Se}_3$  on polycrystalline substrates including fluorine-doped tin oxide (FTO) and  
12 gold. We first determined the appropriate potentials to deposit the orthorhombic phase on each  
13 substrate by performing cyclic voltammetry. Based on the potential-dependent structures of  $\text{Bi}_2\text{Se}_3$   
14 films grown on single-crystal Si substrates, we hypothesized that the orthorhombic phase would  
15 form at a potential positive of the  $\text{Bi}^{3+}$  reduction peak on these polycrystalline substrates. For both  
16 the FTO and Au substrates, an applied potential of 0.00 V vs. Ag/AgCl is positive of the reduction  
17 peak of  $\text{Bi}(\text{NO}_3)_3$  (**Figure S22**). XRD patterns of  $\text{Bi}_2\text{Se}_3$  films grown at this potential for a total  
18 charge density of 2 C/cm<sup>2</sup> are shown in **Figure 10a**. In both cases, we observe the orthorhombic  
19 phase of  $\text{Bi}_2\text{Se}_3$ . The morphology of the orthorhombic crystallites is similar to films deposited on  
20 single-crystal Si substrates. For FTO substrates, both the hemispherical seed layer and interleaved  
21 platelet microcrystals are observed (**Figure 10b, d**). On Au substrates, the seed layer is denser  
22 compared to deposition on Si and FTO substrates, and the orthorhombic  $\text{Bi}_2\text{Se}_3$  crystallites that  
23 grow from this continuous layer have a smaller size for the same amount of material deposited  
24 (**Figure 10c, e**). The transition from island growth of the seed layer on Si and FTO to a smoother  
25 layer on Au is consistent with the higher surface energy of Au in which adatom–substrate  
26 interactions become stronger.<sup>67</sup> These results demonstrate that the spontaneous formation of the  
27  
28  
29  
30  
31  
32  
33  
34  
35  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

seed layer enables electrodeposition of the metastable, orthorhombic phase on a variety of substrates without the requirement for a single crystal.



**Figure 10.** (a) Powder XRD patterns of Bi<sub>2</sub>Se<sub>3</sub> films grown on polycrystalline FTO and Au substrates. The applied potential used to grow the films was 0.00 V vs. Ag/AgCl, and the total amount of charge passed for each film was 2 C/cm<sup>2</sup>. (b, d) SEM images of a Bi<sub>2</sub>Se<sub>3</sub> film grown on FTO. (c, e) SEM images of a Bi<sub>2</sub>Se<sub>3</sub> film grown on Au. The scale bars of 5  $\mu$ m and 1  $\mu$ m apply to all images in the top row and bottom row, respectively.

## Conclusions

In summary, by identifying the conditions needed to form the metastable phase of Bi<sub>2</sub>Se<sub>3</sub> on single-crystal Si substrates, we were able to extend this growth mechanism to polycrystalline substrates including FTO-coated glass and Au. By electrodepositing the films at a potential close to or positive of the peak for Bi<sup>3+</sup> reduction (which varies for different substrates), a seed layer is

1  
2  
3 produced that leads to  $\text{Bi}_2\text{Se}_3$  films with high crystallinity and the metastable, orthorhombic phase.  
4  
5 Electron diffraction reveals that the seed layer contains nanocrystals of cubic BiSe. DFT  
6 calculations indicate that nucleation of the orthorhombic  $\text{Bi}_2\text{Se}_3$  microcrystals takes place on the  
7 cubic BiSe nanocrystals due to epitaxial matching between the two crystals. We hypothesize that  
8 seeded electrochemical growth using nanoscale seed particles can be used to synthesize other  
9 metastable phases of metal chalcogenide and oxide semiconductors. Targets of interest include the  
10 metastable  $\pi$  phase of  $\text{SnS}$ ,<sup>68-69</sup> which is a chiral semiconductor, the metastable  $\epsilon$  phase of  $\text{Ga}_2\text{O}_3$ ,<sup>63</sup>  
11 a ferroelectric semiconductor, and the metastable  $\epsilon$  phase of  $\text{Fe}_2\text{O}_3$ , a multiferroic material.<sup>70</sup> The  
12 ability to produce semiconductor films with metastable crystal structures by electrodeposition at  
13 room temperature without the need for a single-crystal growth substrate can facilitate the  
14 incorporation of these materials into devices for energy and information conversion and storage.  
15  
16  
17  
18  
19  
20  
21  
22  
23  
24  
25  
26  
27  
28  
29  
30

## 31 Experimental section

32

33 **Materials.** All chemicals were used as received. Bismuth (III) nitrate hydrate ( $\text{Bi}(\text{NO}_3)_3 \cdot x\text{H}_2\text{O}$   
34 98%), selenium dioxide ( $\text{SeO}_2$ , 99.4%), platinum gauze (Pt, 100 mesh, 99.9% metals basis), and  
35 Pt wire (0.5 mm diameter, 99.95% metals basis) were purchased from Alfa Aesar. Nitric acid  
36 ( $\text{HNO}_3$ ,  $\geq 97\%$ ), isopropanol ( $\geq 99.7\%$ ), gallium (99.999%), indium beads (99.999%) and sodium  
37 chloride ( $\text{NaCl}$ ,  $\geq 99\%$ ) were purchased from Sigma-Aldrich/Millipore Sigma. All aqueous  
38 solutions were prepared using deionized water from a GenPure Pro water purification system with  
39 a resistivity of  $18.2 \text{ M}\Omega \cdot \text{cm}$ . Single-crystal, n-type Si wafers with either the (100) or (111)  
40 orientation and varying resistivities were purchased from University Wafer, Inc., Addison  
41 Engineering, Inc., and MTI corporation (see **Table S1** in the **Supporting Information** for further  
42 details). FTO-coated glass slides with lateral dimensions of  $1'' \times 1''$ , a thickness of 2.2 mm, and a  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

sheet resistivity of 12 – 14 Ohm/square were purchased from MTI corporation. Chrome-plated tungsten rods and Au pellets (99.999%) were purchased from the Kurt J. Lesker Company. Hydrofluoric acid (49%, LM grade) was purchased from the Transene Company, Inc. Hysol 9460 epoxy was purchased from McMaster-Carr. Silver conductive paint was purchased from SPI Supplies. Acetone ( $\geq$  99.5%) was purchased from Fisher Scientific International, Inc. A eutectic liquid alloy of gallium and indium (Ga–In) was either purchased directly from VWR International, Inc. or prepared by combining the two metals in a weight ratio of approximately 75% Ga and 25% In.

**Preparation of electrodes.** The counter electrode used in all electrochemical experiments consisted of Pt gauze connected to a Pt wire. The Pt wire was soldered to a tinned copper wire, and the soldered joint was sealed in a glass tube. All potentials reported in this manuscript are referenced to a silver/silver chloride (Ag/AgCl) electrode in 3 M NaCl. The working electrodes consisted of single-crystal Si wafers with different orientations and resistivities (see **Table S1** in the **Supporting Information**). The Si wafers were first cut into square pieces with approximate edge lengths of either 5 or 25 mm using a diamond scribe. The larger substrates were used to measure the resistivity of the substrate and to prepare samples for characterization by powder XRD. The smaller substrates were used for all other characterization methods (e.g., thin-film XRD, SEM, TEM, XPS, and CV). To prepare each working electrode, Ga–In eutectic was scratched into the unpolished back side of the Si substrate. A coiled Cu wire was then pressed into the Ga–In liquid on the back side of the Si and coated with conductive Ag paint to seal the wire onto the substrate. Following attachment of the Si substrate, the wire was threaded through a glass tube, and Hysol 9460 epoxy was used to seal the opening of the tube. To cure the epoxy, the electrode was dried

1  
2  
3 in an oven at 60°C. Finally, nail polish was used to coat the unpolished back side of the Si electrode  
4 and the exposed portion of the Cu wire so that the  $\text{Bi}_2\text{Se}_3$  film would only grow on the polished  
5 side of the Si substrate.  
6  
7  
8  
9

10 Polycrystalline Au and FTO films on glass slides were also used as working electrodes to grow  
11  $\text{Bi}_2\text{Se}_3$  films. An Edwards Auto 306 Vacuum Coater was used to deposit the Au films. A 10-nm  
12 adhesion layer of Cr was first deposited on the glass slide at a current of 4.2 A followed by a 100-  
13 nm film of Au at a current of 4 A. The pressure during thermal evaporation was  $10^{-6}$  torr. The Au  
14 and FTO substrates were rinsed with deionized water and dried using a stream of nitrogen prior to  
15 use. For both Au and FTO substrates, a metal alligator clip was used to connect the substrates to  
16 the potentiostat.  
17  
18  
19  
20  
21  
22  
23  
24  
25  
26  
27  
28

29 **Electrochemical synthesis of  $\text{Bi}_2\text{Se}_3$  films.**  $\text{Bi}_2\text{Se}_3$  films were electrodeposited using a three-  
30 electrode configuration at a constant potential with all three electrodes in the same cell. The  
31 deposition procedure was adapted from previous reports.<sup>23-25</sup> The deposition solution contained 1  
32 mM  $\text{Bi}(\text{NO}_3)_3$ , 1.5 mM  $\text{SeO}_2$ , and 0.5 M  $\text{HNO}_3$ . The electrochemical cell was open to air during  
33 deposition. A BioLogic VSP-300 potentiostat/galvanostat was used to perform all electrochemical  
34 experiments. Immediately before each deposition, the polished side of the Si electrode was etched  
35 by immersing it in an aqueous solution of 10% HF for 30 s to remove the native oxide layer. The  
36 electrode was then rinsed with deionized water and dried under a stream of nitrogen. An image of  
37 each electrode was taken using a photo scanner, and the electrode area was measured using ImageJ  
38 software. The electrode area was used to determine the total charge density passed between the  
39 working and counter electrodes during each deposition. The applied potential and the amount of  
40 charge passed were varied for different substrates as described in the manuscript and summarized  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

1  
2  
3 in **Table S2**. After each deposition, the electrode was washed with deionized water and immersed  
4 in acetone to dissolve the nail polish and Ag paint. In some cases, a small amount of Ag redeposited  
5 on the top of the electrode, leading to an impurity observed in the XRD pattern. Once the Si  
6 substrate detached from the wire, it was rinsed with DI water, and dried using a stream of nitrogen  
7 before further characterization.  
8  
9  
10  
11  
12  
13

## 17 Characterization.

18

19 A four-point probe (Keithley 2450 sourcemeter) was used to measure the sheet resistance of  
20 the Si substrates without the contact resistance of the native oxide layer. The distance between  
21 each probe was 1.27 mm. Each Si wafer was first cut into a square piece with dimensions of  
22 approximately 25 mm  $\times$  25 mm, and the exact edge lengths were measured. Source currents  
23 ranging from 1  $\mu$ A to 5 mA were tested. We found that 100  $\mu$ A was the optimal source current for  
24 Si substrates with a resistivity range of 0.001 to 0.006  $\Omega \times$  cm, while 1 mA was the optimal source  
25 current for Si substrates with a resistivity range of 0.5 to 5  $\Omega \times$  cm. The sheet resistivity was  
26 obtained by multiplying the sheet resistance by the thickness of the Si wafer. For each Si wafer,  
27 four measurements were taken on different areas of the substrate, and the values were averaged to  
28 determine the reported resistivity. The resistivities of Au and FTO substrates were measured  
29 through the same method as used for Si substrates. The source current was 1 mA for Au and 10  
30 mA for FTO.  
31  
32  
33  
34  
35  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46

47 Cyclic voltammetry (CV) was performed to characterize the potentials for redox reactions to  
48 occur on different substrates (e.g., single-crystal Si, FTO-coated glass, and polycrystalline Au).  
49 All CV scans started at the open-circuit potential of the electrochemical cell. For each scan, the  
50 potential was first swept from the open-circuit potential to 0 V vs. Ag/AgCl, then swept in the  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

negative direction to  $-0.8$  V, and finally swept back to 0 V, with a scan rate of 20 mV/s. For each substrate, CV scans were performed in both an aqueous solution of 1 mM  $\text{Bi}(\text{NO}_3)_3$  and 0.5 M  $\text{HNO}_3$  as well as a solution of 1.5 mM  $\text{SeO}_2$  and 0.5 M  $\text{HNO}_3$ .

The crystalline phase of each sample was characterized by either powder x-ray diffraction (XRD) in which the film was scraped off from the growth substrate or by thin-film XRD in which the sample was left on the Si substrate. To prepare samples for powder XRD, the  $\text{Bi}_2\text{Se}_3$  film was scraped off using a razor blade, and the powder was redispersed in isopropanol to make a suspension. The suspension was then drop cast onto a zero-background, silicon diffraction plate (MTI Corporation) and left to dry in ambient air. A Bruker D8 Advance x-ray diffractometer ( $\text{Cu K}\alpha = 0.15418$  nm) was used for powder measurements. The scan range was from  $10^\circ$  to  $60^\circ$  in  $2\theta$ , the step size was  $0.035^\circ$  in  $2\theta$ , and the scan rate was 0.4 s per step. Grazing-incidence XRD patterns of the  $\text{Bi}_2\text{Se}_3$  films still on the Si substrates were obtained with a Philips X'Pert diffractometer using  $\text{Cu K}\alpha$  source radiation with an x-ray mirror (PW3088/60) as the incident beam module and a  $0.18^\circ$  parallel plate collimator as the diffracted beam module. A fixed incident angle of  $1^\circ$  was maintained, and the instrument was operated in continuous mode with a step size of  $0.03^\circ$  and a counting time of 2 s.

The morphologies of the  $\text{Bi}_2\text{Se}_3$  films were characterized using a Thermo Scientific Quattro S environmental scanning electron microscope (SEM) operating at an acceleration voltage of 20 kV. For top-down images of the films, the Si substrate was detached from the Cu wire as described above and then affixed to the SEM sample chuck using double-sided Cu tape. An Oxford AzTec energy dispersive x-ray (EDX) spectrometer was used to measure the elemental ratio of selenium and bismuth in each film. EDX spectroscopy was performed at an acceleration voltage of 20 kV. For the cross-sectional SEM images, the Si substrate was first cut in half using a diamond scribe.

1  
2  
3 The back side of the Si substrate was affixed to a vertical sample chuck using Cu tape such that  
4  
5 the cross-section faced up towards the electron beam.  
6  
7

8 A Thermo Scientific Scios 2 Lo Vac Dual Beam FIB-SEM was used to prepare a sample for  
9 cross-sectional TEM and electron diffraction. A layer of Pt (~2 microns) was first deposited on the  
10 region of interest. Then a cross section of the  $\text{Bi}_2\text{Se}_3$  film was cut into a lamella using a 30-kV Ga-  
11 ion beam. The lamella was then attached to a FIB TEM grid in the FIB chamber and polished down  
12 to electron transparency using the Ga-ion beam in steps of 30 kV, 16 kV, 8 kV, 5 kV and 2 kV.  
13 The cross-section foil was characterized by transmission electron microscopy using a JEOL JEM-  
14 2100F field-emission scanning transmission electron microscope operated at an accelerating  
15 voltage of 200 kV. To prepare the powder sample for electron diffraction, the  $\text{Bi}_2\text{Se}_3$  film was  
16 scraped off from the Si substrate and dispersed in approximately 1 mL of isopropanol using  
17 sonication for 10 s. One drop of the suspension was drop cast onto a copper TEM grid and allowed  
18 to dry at room temperature. To obtain electron diffraction patterns, the samples were tilted to be  
19 parallel to the electron beam under the guidance of a Kikuchi pattern. By choosing the high-  
20 symmetry orientation of the Kikuchi pattern, the electron diffraction pattern was produced along  
21 the specific zone axis. We determined the zone axis of the obtained electron diffraction pattern by  
22 comparing it with a simulated diffraction pattern. Dark-field images were recorded by selecting  
23 the diffraction spots formed on the back focal plane of the objective lens using the smallest  
24 objective-lens aperture.  
25  
26

27 To prepare each sample for x-ray photoelectron spectroscopy (XPS), the Si substrate with  
28  $\text{Bi}_2\text{Se}_3$  film was cut into a smaller piece of approximately 2 mm  $\times$  2 mm. XPS was performed  
29 using a Physical Electronics 5000 Versa Probe II Scanning ESCA (XPS) Microprobe system with  
30 a base pressure below  $10^{-8}$  Pa. XPS data were acquired using the 1486.6 eV line from a  
31  
32  
33  
34  
35  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

1  
2  
3 monochromatic Al K $\alpha$  source with a spherical capacitor analyzer set to a pass energy of 23.5 eV  
4 for the high-resolution scans. The beam size was 100  $\mu\text{m}$  in diameter, the beam power was 25 W,  
5 and the acceleration voltage was 15 kV. The step size was 0.05 eV, and the number of sweeps was  
6 20 cycles for carbon and 30 cycles for all other elements. To remove the oxide layer that forms on  
7 the surface of the films when left out in air, each sample was first pre-sputtered by sweeping the  
8 surface of the film with an Ar-ion beam at an acceleration voltage of 2 kV and a current of 1  $\mu\text{A}$   
9 for 2 min. All spectra were charge corrected using the carbon peak (284.6 eV). The deconvolution  
10 of peaks in the spectra were fit by using XPSPEAK software with a Shirley background. The areas  
11 of peaks during the deconvolution were constrained to be close to the expected area ratio based on  
12 the degeneracy of each spin state.  
13  
14  
15  
16  
17  
18  
19  
20  
21  
22  
23  
24  
25  
26  
27  
28  
29

## Calculation methods

30 Density-functional-theory (DFT) calculations were performed using the Vienna Ab Initio  
31 Simulation Package (VASP)<sup>71</sup> with the projector augmented-wave potentials (PAW).<sup>72</sup> We used  
32 the Perdew–Burke–Ernzerhof functional revised for solids (PBEsol)<sup>73</sup> to describe the exchange-  
33 correlation interactions. A plane-wave basis with cutoff energy of 520 eV and force tolerance  
34 criterion of 0.01 eV/ $\text{\AA}$  on each atom was used. Initial structures of orthorhombic and rhombohedral  
35 Bi<sub>2</sub>Se<sub>3</sub> and rock salt and trigonal BiSe (**Figure S16**) were downloaded from the ICSD. We used  
36  $\Gamma$ -centered Monkhorst-Pack  $k$ -point meshes to sample the Brillouin zone.<sup>74</sup> The number of  $k$ -points  
37 along direction  $i$  was varied such that  $k_i \times a_i$ , where  $a_i$  is the lattice parameter along direction  $i$ , was  
38 ~30 for geometry optimization and ~60 for the static calculations. For the strain calculations,  
39 supercells of Bi<sub>2</sub>Se<sub>3</sub> were constructed with different orientations while keeping the stoichiometry  
40 of Bi:Se to 2:3. Then, the  $a$  and  $b$  lattice parameters of the supercell were changed to match with  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

the smallest repeating unit of the theoretical cubic BiSe (100) surface ( $a_{\text{sub}} = 6.07 \text{ \AA}$ ). We used the equation below to calculate the formation enthalpy ( $\delta H$ ) of the rhombohedral and orthorhombic  $\text{Bi}_2\text{Se}_3$  supercells with epitaxially constrained lattice parameters:

$$\delta H = E(\text{Bi}_{2n}\text{Se}_{3n}) - (2n \times E(\text{Bi}) + 3n \times E(\text{Se})).$$

Here,  $E(\text{Bi}_{2n}\text{Se}_{3n})$  is the total energy of the  $\text{Bi}_{2n}\text{Se}_{3n}$  supercell with different orientations.  $E(\text{Bi})$  and  $E(\text{Se})$  are, respectively, the energy of one Bi atom in its stable trigonal phase and one Se atom in its stable monoclinic phase.

For the coincident site lattice calculations, the lattice parameters of the  $\text{Bi}_2\text{Se}_3$  supercells were adjusted to perfectly match with the cubic BiSe (001) substrate. For example, as shown in **Figure S19**, orthorhombic  $\text{Bi}_2\text{Se}_3$  with the (010) surface is matched with the cubic BiSe (001) surface. To perfectly match with the lattice parameter  $a_{\text{sub}}$  of the substrate (the relationship between  $a_{\text{unit}}$  and  $a_{\text{sub}}$  is shown in **Figure S16b**), we apply a strain  $\delta$  to axes  $a_{[001]}$  and  $a_{[100]}$  of  $\text{Bi}_2\text{Se}_3$  such that:

$$a_{[001]} + \delta_{[001]} = 2\sqrt{2}a_{\text{unit}} = 2a_{\text{sub}}$$

$$a_{[100]} + \delta_{[100]} = 2\sqrt{2}a_{\text{unit}} = 2a_{\text{sub}}$$

Since the experimental lattice parameter of the cubic BiSe nanocrystals is expected to vary over a range of values, we applied a variance  $\delta_{\text{sub}}$  to the calculated lattice parameter of cubic BiSe. Thus, the lengths along the [001] and [100] dimensions of  $\text{Bi}_2\text{Se}_3$  are changed as follows:

$$a_{[001]} + \delta_{[001]} = 2(a_{\text{sub}} + \delta_{\text{sub}})$$

$$a_{[100]} + \delta_{[100]} = 2(a_{\text{sub}} + \delta_{\text{sub}})$$

The strains applied along each direction of orthorhombic  $\text{Bi}_2\text{Se}_3$  are:

$$\delta_{[001]} = 2(a_{\text{sub}} + \delta_{\text{sub}}) - a_{[001]}$$

$$\delta_{[100]} = 2(a_{\text{sub}} + \delta_{\text{sub}}) - a_{[100]}$$

1  
2  
3 Thus, the formation energy of orthorhombic  $\text{Bi}_2\text{Se}_3$  with the (010) surface is changed according to  
4  
5 the strain applied along each dimension.  
6

7  
8 Bader charge analysis for a series of bismuth selenide and bismuth oxide compounds was  
9  
10 performed using the method developed by Tang *et al.*<sup>75</sup> The Bader charges of Bi, Se, and O in the  
11  
12 different compounds listed in **Table S4** were obtained by subtracting the number of valence  
13  
14 electrons of an atom within the PAW potential from the number of electrons assigned to the  
15  
16 corresponding atom after the charge density partition. If the difference in Bader charge for atoms  
17  
18 of a species was greater than 0.1, we classified them into separate groups. The Bader charge was  
19  
20 averaged among atoms within the same group.  
21  
22

23  
24 To determine the relative stabilities of cubic and trigonal BiSe nanocrystals as a function of  
25 size, we first computed the energies of various low-index surfaces of cubic and trigonal BiSe using  
26 slab models having a vacuum region of at least 15 Å in thickness. These slabs have symmetric top  
27 and bottom surfaces (see the Data Availability Statement below for a link that provides the slab  
28 models). The calculated surface energies were used within the WulffPack program<sup>76</sup> to create  
29 equilibrium crystal morphologies, as shown in **Figure S21a** and **b**. To compare the energies of  
30 cubic and trigonal BiSe nanocrystals — that have different shapes and numbers of atoms — as a  
31 function of their size, we calculated the Gibbs formation energy,  $E(R)$ , using the formula shown  
32 below:<sup>77</sup>  
33  
34

$$E(R) = E_{\text{Bulk}} + \left(\frac{1}{R}\right)\eta\rho\gamma,$$

35  
36  
37  
38 where  $E_{\text{Bulk}}$  is the bulk formation energy per BiSe unit (eV/BiSe) — it is the same as the formation  
39  
40 enthalpy, as we ignore the entropic and zero-point energy contributions to the free energy,  $R$  is the  
41  
42 “effective radius” of the nanocrystal,  $\eta$  is a unitless shape factor used to compare nanocrystals of  
43  
44 different shapes,<sup>78</sup>  $\rho$  is the density of the BiSe nanocrystal, which is the total volume normalized  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

1  
2  
3 per BiSe formula unit ( $\text{\AA}^3/\text{BiSe}$ ), and  $\gamma$  is the surface energy averaged over the nanocrystal (eV/ $\text{\AA}^2$ ).  
4  
5

6 The computed values of  $E_{\text{Bulk}}$ ,  $\eta$ ,  $\rho$ , and  $\gamma$  are shown in the **Table S7**. The shape factor  $\eta = S/V^{2/3}$ ,  
7 where  $S$  is the total surface area and  $V$  is the volume of the equilibrium morphology. Different  
8 equilibrium morphologies have their own shape factor.<sup>77</sup> We plotted the total surface area as a  
9 function of the volume<sup>2/3</sup> for the equilibrium morphologies of cubic and trigonal BiSe (see **Figure**  
10  
11  
12  
13  
14  
15 **21c**), and the slope of each trace gives the shape factor.  
16  
17  
18

19 Supporting Information Available:  
20

21 Supporting discussion of Bader charge analysis of bismuth selenide and oxide compounds; the  
22 search process used to find Bi–Se compounds in the ICSD and identify the structure of seed layer;  
23 the formation enthalpy of orthorhombic and rhombohedral  $\text{Bi}_2\text{Se}_3$  when interfaced with the (110)  
24 surface of cubic BiSe; size dependence of the relative stabilities of cubic and trigonal BiSe  
25 nanocrystals. Supporting tables providing the orientation, resistivity, and thickness of the Si  
26 substrates used to grow  $\text{Bi}_2\text{Se}_3$  films, the electrodeposition parameters used to grow  $\text{Bi}_2\text{Se}_3$  films,  
27 binding energies for Bi 4f x-ray photoelectron peaks after deconvolution of the spectra into  
28 contributions from different oxidation states, the Bader charge of Bi, Se, and O in bismuth selenide  
29 and oxide compounds, a summary of the structures of compounds containing Bi and Se from the  
30 ICSD, calculated surface energies of cubic BiSe, trigonal BiSe, orthorhombic  $\text{Bi}_2\text{Se}_3$ , and  
31 rhombohedral  $\text{Bi}_2\text{Se}_3$ , calculated average surface energy, shape factor, volume per BiSe unit, and  
32 bulk formation enthalpy for cubic and trigonal BiSe; Supporting figures showing current traces  
33 during the electrodeposition of the  $\text{Bi}_2\text{Se}_3$  films, powder XRD patterns of  $\text{Bi}_2\text{Se}_3$  films grown on  
34 Si substrates with different orientations and resistivities, cyclic voltammograms in a solution of  
35  $\text{SeO}_2$  and  $\text{HNO}_3$  using different Si substrates as the working electrode, SEM image and thin-film  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

1  
2  
3 XRD pattern of the seed layer formed during the initial growth stage, SEM images of  
4 rhombohedral  $\text{Bi}_2\text{Se}_3$  films grown for different charge densities, additional XPS results for  $\text{Bi}_2\text{Se}_3$   
5 films with the orthorhombic and rhombohedral structures, plots of the Bader charge of Bi in  
6 different bismuth selenide and oxide compounds, the unit cells of cubic and trigonal BiSe and the  
7 smallest repeating unit on the cubic BiSe (001) surface, a simulated electron diffraction pattern of  
8  $\text{Bi}_2\text{Se}_3$  with the  $\text{Zn}_3\text{P}_2$  structure, additional cross-sectional TEM images and electron diffraction  
9 patterns of a  $\text{Bi}_2\text{Se}_3$  film, coincident site lattice models for different surfaces of rhombohedral and  
10 orthorhombic  $\text{Bi}_2\text{Se}_3$  matched with the cubic BiSe (001) surface, change in the formation enthalpy  
11 of rhombohedral and orthorhombic  $\text{Bi}_2\text{Se}_3$  matched with the cubic BiSe (110) surface as a function  
12 of the substrate lattice parameter, the equilibrium morphologies and Gibbs formation energy of  
13 cubic and trigonal BiSe nanocrystals, cyclic voltammograms in a solution of  $\text{Bi}(\text{NO}_3)_3$  and  $\text{HNO}_3$   
14 using Au and FTO substrates as the working electrode.

15  
16  
17  
18  
19  
20  
21  
22  
23  
24  
25  
26  
27  
28  
29  
30  
31  
32  
33 Data Availability Statement.

34  
35 The data underlying this study are openly available in Zenodo at  
36  
37 <https://zenodo.org/record/6987295#.Yvqd4-zMIXp>

38  
39  
40  
41  
42 Acknowledgements.

43  
44 This material is based upon work supported by the National Science Foundation (NSF) under  
45 grant no. CHE-1753344 to B.S.; and CBET-1729787, DMR-1806147 and DMR-2122070 to R.M.  
46 Electron microscopy, focused ion-beam milling, and x-ray photoelectron spectroscopy were  
47 performed at the Institute of Materials Science & Engineering at Washington University. Powder  
48 x-ray diffraction was performed in the Department of Earth and Planetary Sciences at Washington  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

1  
2  
3 University. Thin-film XRD was performed at the Advanced Materials Characterization Laboratory  
4 at the Missouri University of Science and Technology. B.M.C. acknowledges support from the  
5 MARC U-STAR program at Washington University. The authors thank J. D'Arcy and Y. Lu for  
6  
7 use of their 4-point probe apparatus.  
8  
9  
10  
11  
12  
13  
14  
15  
16  
17  
18  
19  
20  
21  
22  
23  
24  
25  
26  
27  
28  
29  
30  
31  
32  
33  
34  
35  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

1  
2  
3 **References**  
4

5 1. Wang, Z.; Hou, J.; Yang, C.; Jiao, S.; Huang, K.; Zhu, H., Hierarchical Metastable  $\gamma$ -TaON  
6 Hollow Structures for Efficient Visible-Light Water Splitting. *Energy & Environmental*  
7 *Science* **2013**, *6*, 2134-2144.

8 2. Shao, Q.; Wang, Y.; Yang, S.; Lu, K.; Zhang, Y.; Tang, C.; Song, J.; Feng, Y.; Xiong, L.;  
9 Peng, Y.; Li, Y.; Xin, H. L.; Huang, X., Stabilizing and Activating Metastable Nickel  
10 Nanocrystals for Highly Efficient Hydrogen Evolution Electrocatalysis. *ACS Nano* **2018**, *12*,  
11 11625-11631.

12 3. Wang, Y.; Sun, D.; Chowdhury, T.; Wagner, J. S.; Kempa, T. J.; Hall, A. S., Rapid Room-  
13 Temperature Synthesis of a Metastable Ordered Intermetallic Electrocatalyst. *Journal of the*  
14 *American Chemical Society* **2019**, *141*, 2342-2347.

15 4. Duan, Y.; Sun, S.; Sun, Y.; Xi, S.; Chi, X.; Zhang, Q.; Ren, X.; Wang, J.; Ong, S. J. H.; Du,  
16 Y.; Gu, L.; Grimaud, A.; Xu, Z. J., Mastering Surface Reconstruction of Metastable Spinel  
17 Oxides for Better Water Oxidation. *Advanced Materials* **2019**, *31*, 1807898.

18 5. Zhang, S.; Huang, Z.; Wen, Z.; Zhang, L.; Jin, J.; Shahbazian-Yassar, R.; Yang, J., Local  
19 Lattice Distortion Activate Metastable Metal Sulfide as Catalyst with Stable Full Discharge-  
20 Charge Capability for Li–O<sub>2</sub> Batteries. *Nano Letters* **2017**, *17*, 3518-3526.

21 6. Higgins, D.; Wette, M.; Gibbons, B. M.; Siahrostami, S.; Hahn, C.; Escudero-Escribano, M.;  
22 García-Melchor, M.; Ulissi, Z.; Davis, R. C.; Mehta, A.; Clemens, B. M.; Nørskov, J. K.;  
23 Jaramillo, T. F., Copper Silver Thin Films with Metastable Miscibility for Oxygen Reduction  
24 Electrocatalysis in Alkaline Electrolytes. *ACS Applied Energy Materials* **2018**, *1*, 1990-1999.

1  
2  
3 7. Zu, C.; Wang, W. B.; He, L.; Zhang, W. G.; Dai, C. Y.; Wang, F.; Duan, L. M., Experimental  
4 Realization of Universal Geometric Quantum Gates with Solid-State Spins. *Nature* **2014**, *514*,  
5 72-75.  
6  
7 8. Pezzagna, S.; Meijer, J., Quantum Computer Based on Color Centers in Diamond. *Applied  
8 Physics Reviews* **2021**, *8*, 011308.  
9  
10 9. Yan, C.-s.; Vohra, Y. K.; Mao, H.-k.; Hemley, R. J., Very High Growth Rate Chemical Vapor  
11 Deposition of Single-Crystal Diamond. *Proceedings of the National Academy of Sciences  
12* **2002**, *99*, 12523-12525.  
13  
14 10. Rabeau, J. R.; Stacey, A.; Rabeau, A.; Prawer, S.; Jelezko, F.; Mirza, I.; Wrachtrup, J., Single  
15 Nitrogen Vacancy Centers in Chemical Vapor Deposited Diamond Nanocrystals. *Nano  
16 Letters* **2007**, *7*, 3433-3437.  
17  
18 11. Achard, J.; Jacques, V.; Tallaire, A., Chemical Vapour Deposition Diamond Single Crystals  
19 with Nitrogen-Vacancy Centres: A Review of Material Synthesis and Technology for  
20 Quantum Sensing Applications. *Journal of Physics D: Applied Physics* **2020**, *53*, 313001.  
21  
22 12. Kucska, G.; Maurer, P. C.; Yao, N. Y.; Kubo, M.; Noh, H. J.; Lo, P. K.; Park, H.; Lukin, M.  
23 D., Nanometre-Scale Thermometry in a Living Cell. *Nature* **2013**, *500*, 54-58.  
24  
25 13. Sines, I. T.; Misra, R.; Schiffer, P.; Schaak, R. E., Colloidal Synthesis of Non-Equilibrium  
26 Wurtzite-Type MnSe. *Angewandte Chemie International Edition* **2010**, *49*, 4638-4640.  
27  
28 14. Bergerud, A.; Buonsanti, R.; Jordan-Sweet, J. L.; Milliron, D. J., Synthesis and Phase Stability  
29 of Metastable Bixbyite V<sub>2</sub>O<sub>3</sub> Colloidal Nanocrystals. *Chemistry of Materials* **2013**, *25*, 3172-  
30 3179.  
31  
32  
33  
34  
35  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

1  
2  
3 15. Martinolich, A. J.; Kurzman, J. A.; Neilson, J. R., Polymorph Selectivity of Superconducting  
4 CuSe<sub>2</sub> through Kinetic Control of Solid-State Metathesis. *Journal of the American Chemical  
5 Society* **2015**, *137*, 3827-3833.  
6  
7  
8  
9  
10 16. Martinolich, A. J.; Kurzman, J. A.; Neilson, J. R., Circumventing Diffusion in Kinetically  
11 Controlled Solid-State Metathesis Reactions. *Journal of the American Chemical Society* **2016**,  
12 *138*, 11031-11037.  
13  
14  
15 17. Tochitskii, T. A.; Shadrow, V. G.; Nemtsevich, L. V.; Boltushkin, A. V., On the Mechanism  
16 of Metastable Phases' Formation in Electrodeposited Co-Based Films. *Crystal Research and  
17 Technology* **1996**, *31*, 583-588.  
18  
19  
20  
21  
22 18. Cavallotti, P. L.; Nobili, L.; Vicenzo, A., Phase Structure of Electrodeposited Alloys.  
23  
24 *Electrochimica Acta* **2005**, *50*, 4557-4565.  
25  
26  
27 19. Wang, T.; Li, F.; Wang, Y.; Song, L., Structure and Magnetic Properties of Metastable Co–  
28 Cu Solid Solution Nanowire Arrays Fabricated by Electrodeposition. *physica status solidi (a)*  
29 **2006**, *203*, 2426-2431.  
30  
31  
32  
33 20. Crozier, B.; Liu, Q.; Ivey, D. G., Formation and Transformation of Metastable Phases During  
34 Electrodeposition and Annealing of Cobalt–Iron Alloy Films. *Journal of Materials Science:*  
35  
36 *Materials in Electronics* **2011**, *22*, 614-625.  
37  
38  
39  
40 21. Switzer, J. A.; Shumsky, M. G.; Bohannan, E. W., Electrodeposited Ceramic Single Crystals.  
41  
42 *Science* **1999**, *284*, 293-296.  
43  
44  
45 22. Mathe, M. K.; Cox, S. M.; Flowers, B. H.; Vaidyanathan, R.; Pham, L.; Srisook, N.; Happek,  
46 U.; Stickney, J. L., Deposition of CdSe by EC-ALE. *Journal of Crystal Growth* **2004**, *271*,  
47  
48 55-64.  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

1  
2  
3 23. Tumelero, M. A.; Benetti, L. C.; Isoppo, E.; Faccio, R.; Zangari, G.; Pasa, A. A.,  
4 Electrodeposition and *ab Initio* Studies of Metastable Orthorhombic  $\text{Bi}_2\text{Se}_3$ : A Novel  
5 Semiconductor with Bandgap for Photovoltaic Applications. *The Journal of Physical*  
6  
7 *Chemistry C* **2016**, *120*, 11797-11806.  
8  
9 24. Souza, P. B.; Tumelero, M. A.; Zangari, G.; Pasa, A. A., Tuning Electrodeposition Conditions  
10 Towards the Formation of Smooth  $\text{Bi}_2\text{Se}_3$  Thin Films. *Journal of The Electrochemical Society*  
11 **2017**, *164*, D401-D405.  
12  
13 25. Ahmed, R.; Lin, Q.; Xu, Y.; Zangari, G., Growth, Morphology and Crystal Structure of  
14 Electrodeposited  $\text{Bi}_2\text{Se}_3$  Films: Influence of the Substrate. *Electrochimica Acta* **2019**, *299*,  
15 654-662.  
16  
17 26. Sorenson, T. A.; Morton, S. A.; Waddill, G. D.; Switzer, J. A., Epitaxial Electrodeposition of  
18  $\text{Fe}_3\text{O}_4$  Thin Films on the Low-Index Planes of Gold. *Journal of the American Chemical*  
19  
20 *Society* **2002**, *124*, 7604-7609.  
21  
22  
23 27. Villegas, I.; Stickney, J. L., Preliminary Studies of GaAs Deposition on Au(100), (110), and  
24 (111) Surfaces by Electrochemical Atomic Layer Epitaxy. *Journal of The Electrochemical*  
25  
26 *Society* **1992**, *139*, 686-694.  
27  
28 28. Golden, T. D.; Shumsky, M. G.; Zhou, Y.; VanderWerf, R. A.; Van Leeuwen, R. A.; Switzer,  
29 J. A., Electrochemical Deposition of Copper(I) Oxide Films. *Chemistry of Materials* **1996**, *8*,  
30 2499-2504.  
31  
32 29. Carim, A. I.; Collins, S. M.; Foley, J. M.; Maldonado, S., Benchtop Electrochemical Liquid–  
33 Liquid–Solid Growth of Nanostructured Crystalline Germanium. *Journal of the American*  
34  
35 *Chemical Society* **2011**, *133*, 13292-13295.  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

1  
2  
3 30. Fahrenkrug, E.; Gu, J.; Maldonado, S., Electrodeposition of Crystalline GaAs on Liquid  
4 Gallium Electrodes in Aqueous Electrolytes. *Journal of the American Chemical Society* **2013**,  
5 135, 330-339.  
6  
7 31. Kim, T. W.; Woo, M. A.; Regis, M.; Choi, K.-S., Electrochemical Synthesis of Spinel Type  
8 ZnCo<sub>2</sub>O<sub>4</sub> Electrodes for Use as Oxygen Evolution Reaction Catalysts. *The Journal of Physical*  
9 *Chemistry Letters* **2014**, 5, 2370-2374.  
10  
11 32. Lowe, James M.; Yan, Q.; Benamara, M.; Coridan, R. H., Direct Photolithographic Patterning  
12 of Cuprous Oxide Thin Films Via Photoelectrodeposition. *Journal of Materials Chemistry A*  
13 **2017**, 5, 21765-21772.  
14  
15 33. Wheeler, G. P.; Choi, K.-S., Photoelectrochemical Properties and Stability of Nanoporous p-  
16 Type LaFeO<sub>3</sub> Photoelectrodes Prepared by Electrodeposition. *ACS Energy Letters* **2017**, 2,  
17 2378-2382.  
18  
19 34. Banik, A.; Tubbesing, J. Z.; Luo, B.; Zhang, X.; Switzer, J. A., Epitaxial Electrodeposition of  
20 Optically Transparent Hole-Conducting CuI on n-Si(111). *Chemistry of Materials* **2021**, 33,  
21 3220-3227.  
22  
23 35. Kang, D.; Kim, T. W.; Kubota, S. R.; Cardiel, A. C.; Cha, H. G.; Choi, K.-S., Electrochemical  
24 Synthesis of Photoelectrodes and Catalysts for Use in Solar Water Splitting. *Chemical*  
25 *Reviews* **2015**, 115, 12839-12887.  
26  
27 36. Fahrenkrug, E.; Maldonado, S., Electrochemical Liquid–Liquid–Solid (ec-LLS) Crystal  
28 Growth: A Low-Temperature Strategy for Covalent Semiconductor Crystal Growth. *Accounts*  
29 *of Chemical Research* **2015**, 48, 1881-1890.  
30  
31 37. Sarkar, D.; Wang, W.; Mecklenburg, M.; Clough, A. J.; Yeung, M.; Ren, C.; Lin, Q.;  
32 Blankemeier, L.; Niu, S.; Zhao, H.; Shi, H.; Wang, H.; Cronin, S. B.; Ravichandran, J.; Luhar,  
33  
34  
35  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

1  
2  
3 M.; Kapadia, R., Confined Liquid-Phase Growth of Crystalline Compound Semiconductors  
4 on Any Substrate. *ACS Nano* **2018**, *12*, 5158-5167.

5  
6  
7 38. Konstantatos, G.; Levina, L.; Tang, J.; Sargent, E. H., Sensitive Solution-Processed  $\text{Bi}_2\text{S}_3$   
8 Nanocrystalline Photodetectors. *Nano Letters* **2008**, *8*, 4002-4006.

9  
10 39. Xu, J.; Li, H.; Fang, S.; Jiang, K.; Yao, H.; Fang, F.; Chen, F.; Wang, Y.; Shi, Y., Synthesis  
11 of Bismuth Sulfide Nanobelts for High Performance Broadband Photodetectors. *Journal of*  
12  
13 *Materials Chemistry C* **2020**, *8*, 2102-2108.

14  
15 40. Filip, M. R.; Patrick, C. E.; Giustino, F., *GW* Quasiparticle Band Structures of Stibnite,  
16 Antimonselite, Bismuthinite, and Guanajuatite. *Physical Review B* **2013**, *87*, 205125.

17  
18 41. Biswas, K.; Zhao, L.-D.; Kanatzidis, M. G., Tellurium-Free Thermoelectric: The Anisotropic  
19  
20 *n*-Type Semiconductor  $\text{Bi}_2\text{S}_3$ . *Advanced Energy Materials* **2012**, *2*, 634-638.

21  
22 42. Liu, W.; Lukas, K. C.; McEnaney, K.; Lee, S.; Zhang, Q.; Opeil, C. P.; Chen, G.; Ren, Z.,  
23 Studies on the  $\text{Bi}_2\text{Te}_3$ - $\text{Bi}_2\text{Se}_3$ - $\text{Bi}_2\text{S}_3$  System for Mid-Temperature Thermoelectric Energy  
24 Conversion. *Energy & Environmental Science* **2013**, *6*, 552-560.

25  
26 43. Witting, I. T.; Chasapis, T. C.; Ricci, F.; Peters, M.; Heinz, N. A.; Hautier, G.; Snyder, G. J.,  
27 The Thermoelectric Properties of Bismuth Telluride. *Advanced Electronic Materials* **2019**, *5*,  
28 1800904.

29  
30 44. Ahmed, R.; Rosul, M. G.; Xu, Y.; Zebarjadi, M.; Zangari, G., Morphology and Seebeck  
31 Coefficients of Electrodeposited  $\text{Bi}_2\text{Se}_3$  Films Grown onto Au(111)/Si Substrates.  
32  
33 *Electrochimica Acta* **2021**, *368*, 137554.

34  
35 45. Zhang, H.; Liu, C.-X.; Qi, X.-L.; Dai, X.; Fang, Z.; Zhang, S.-C., Topological Insulators in  
36  $\text{Bi}_2\text{Se}_3$ ,  $\text{Bi}_2\text{Te}_3$  and  $\text{Sb}_2\text{Te}_3$  with a Single Dirac Cone on the Surface. *Nature Physics* **2009**, *5*,  
37 438-442.

38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

1  
2  
3 46. Jeong, K.; Park, H.; Chae, J.; Sim, K.-i.; Yang, W. J.; Kim, J.-h.; Hong, S.-b.; Kim, J. H.;  
4 Cho, M.-h., Topological Phase Control of Surface States in  $\text{Bi}_2\text{Se}_3$  via Spin–Orbit Coupling  
5 Modulation through Interface Engineering between  $\text{HfO}_{2-x}$ . *ACS Applied Materials &*  
6 *Interfaces* **2020**, *12*, 12215-12226.  
7  
8 47. Tan, D.; Zhang, W.; Wang, X.; Koirala, S.; Miyauchi, Y.; Matsuda, K., Polarization-Sensitive  
9 and Broadband Germanium Sulfide Photodetectors with Excellent High-Temperature  
10 Performance. *Nanoscale* **2017**, *9*, 12425-12431.  
11  
12 48. Chen, S.; Cao, R.; Chen, X.; Wu, Q.; Zeng, Y.; Gao, S.; Guo, Z.; Zhao, J.; Zhang, M.; Zhang,  
13 H., Anisotropic Plasmonic Nanostructure Induced Polarization Photoresponse for  $\text{MoS}_2$ -  
14 Based Photodetector. *Advanced Materials Interfaces* **2020**, *7*, 1902179.  
15  
16 49. Tumelero, M. A.; Martins, M. B.; Souza, P. B.; Della Pace, R. D.; Pasa, A. A., Effect of  
17 Electrolyte on the Growth of Thermoelectric  $\text{Bi}_2\text{Se}_3$  Thin Films. *Electrochimica Acta* **2019**,  
18 *300*, 357-362.  
19  
20 50. Torane, A. P.; Lokhande, C. D.; Patil, P. S.; Bhosale, C. H., Preparation and Characterization  
21 of Electrodeposited  $\text{Bi}_2\text{Se}_3$  Thin Films. *Materials Chemistry and Physics* **1998**, *55*, 51-54.  
22  
23 51. Desai, J. D., Electrodeposition of  $\text{Bi}_2\text{Se}_3$  Thin Films. *Bulletin of Electrochemistry* **1999**, *15*,  
24 315-317.  
25  
26 52. Xiao, C.; Yang, J.; Zhu, W.; Peng, J.; Zhang, J., Electrodeposition and Characterization of  
27  $\text{Bi}_2\text{Se}_3$  Thin Films by Electrochemical Atomic Layer Epitaxy (ECALE). *Electrochimica Acta*  
28 **2009**, *54*, 6821-6826.  
29  
30 53. Peng, H.; Zhou, J.; Tang, D.; Lai, Y.; Liu, F.; Li, J.; Liu, Y., Preparation and Characterization  
31 of  $\text{Bi}_2\text{Se}_3$  Nanowires by Electrodeposition. *Electrochimica Acta* **2011**, *56*, 5085-5089.  
32  
33  
34  
35  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

1  
2  
3 54. Li, J.; Wang, B.; Liu, F.; Liu, J.; Jia, M.; Lai, Y.; Li, J.; Liu, Y., Structural and Optical  
4 Properties of Electrodeposited  $\text{Bi}_{2-x}\text{Sb}_x\text{Se}_3$  Thin Films. *ECS Solid State Letters* **2012**, *1*, Q29-  
5 Q31.  
6  
7 55. Han, C.; Yang, J.; Yan, C.; Li, Y.; Liu, F.; Jiang, L.; Ye, J.; Liu, Y., The Electrochemical Self-  
8 Assembly of Hierarchical Dendritic  $\text{Bi}_2\text{Se}_3$  Nanostructures. *CrystEngComm* **2014**, *16*, 2823-  
9 2834.  
10  
11 56. Inorganic Crystal Structure Database <https://icsd.products.fiz-karlsruhe.de/> (accessed 2022-  
12 04-01).  
13  
14 57. Ahmed, R.; Xu, Y.; Sales, M. G.; Lin, Q.; McDonnell, S.; Zangari, G., Synthesis and Material  
15 Properties of  $\text{Bi}_2\text{Se}_3$  Nanostructures Deposited by SILAR. *The Journal of Physical Chemistry C* **2018**, *122*, 12052-12060.  
16  
17 58. Li, Y.; Cheng, J.; Song, J.; Alonso, J. A.; Fernández-Díaz, M. T.; Goodenough, J. B.,  
18 Characterization of the Double Perovskite  $\text{Ba}_2\text{Bi}_x\text{Sc}_{0.2}\text{Co}_{1.8-x}\text{O}_{6-\delta}$  ( $x = 0.1, 0.2$ ). *Chemistry of*  
19 *Materials* **2012**, *24*, 4114-4122.  
20  
21 59. Li, H.; Shang, J.; Zhu, H.; Yang, Z.; Ai, Z.; Zhang, L., Oxygen Vacancy Structure Associated  
22 Photocatalytic Water Oxidation of  $\text{BiOCl}$ . *ACS Catalysis* **2016**, *6*, 8276-8285.  
23  
24 60. Bhachu, D. S.; Moniz, S. J. A.; Sathasivam, S.; Scanlon, D. O.; Walsh, A.; Bawaked, S. M.;  
25 Mokhtar, M.; Obaid, A. Y.; Parkin, I. P.; Tang, J.; Carmalt, C. J., Bismuth Oxyhalides:  
26 Synthesis, Structure and Photoelectrochemical Activity. *Chemical Science* **2016**, *7*, 4832-  
27 4841.  
28  
29 61. Mao, C.; Cheng, H.; Tian, H.; Li, H.; Xiao, W.-J.; Xu, H.; Zhao, J.; Zhang, L., Visible Light  
30 Driven Selective Oxidation of Amines to Imines with  $\text{BiOCl}$ : Does Oxygen Vacancy  
31 Concentration Matter? *Applied Catalysis B: Environmental* **2018**, *228*, 87-96.  
32  
33  
34  
35  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

1  
2  
3 62. Vasileiadis, T.; Skountzos, E. N.; Foster, D.; Coleman, S. P.; Zahn, D.; Krečinić, F.;  
4 Mavrantzas, V. G.; Palmer, R. E.; Ernstorfer, R., Ultrafast Rotational Motions of Supported  
5 Nanoclusters Probed by Electron Diffraction. *Nanoscale Horizons* **2019**, *4*, 1164-1173.  
6  
7  
8  
9  
10 63. Cho, S. B.; Mishra, R., Epitaxial Engineering of Polar  $\epsilon$ -Ga<sub>2</sub>O<sub>3</sub> for Tunable Two-  
11 Dimensional Electron Gas at the Heterointerface. *Applied Physics Letters* **2018**, *112*, 162101.  
12  
13  
14 64. Semiletov, S. A., An Electron Diffraction Study of Films of Bi-Se and Bi-Te Prepared by  
15 Evaporation. *Trudy Instituta Kristallografi, Akademiya Nauk SSSR* **1954**, *10*, 76-83.  
16  
17  
18 65. Trump, B. A.; Livi, K. J. T.; McQueen, T. M., The New Misfit Compound (BiSe)<sub>1.15</sub>(TiSe<sub>2</sub>)<sub>2</sub>  
19 and the Role of Dimensionality in the Cu<sub>x</sub>(BiSe)<sub>1+δ</sub>(TiSe<sub>2</sub>)<sub>n</sub> Series. *Journal of Solid State*  
20  
21  
22  
23  
24 Chemistry **2014**, *209*, 6-12.  
25  
26 66. Lygo, A. C.; Hamann, D. M.; Moore, D. B.; Merrill, D. R.; Ditto, J.; Esters, M.; Orlowicz, J.;  
27 Wood, S. R.; Johnson, D. C., Kinetically Controlled Formation and Decomposition of  
28 Metastable [(BiSe)<sub>1+δ</sub>]<sub>m</sub>[TiSe<sub>2</sub>]<sub>m</sub> Compounds. *Journal of the American Chemical Society* **2018**,  
29  
30  
31  
32  
33  
34 140, 3385-3393.  
35  
36 67. Penner, R. M., Mesoscopic Metal Particles and Wires by Electrodeposition. *The Journal of*  
37  
38 *Physical Chemistry B* **2002**, *106*, 3339-3353.  
39  
40  
41 68. Rabkin, A.; Samuha, S.; Abutbul, R. E.; Ezersky, V.; Meshi, L.; Golan, Y., New  
42 Nanocrystalline Materials: A Previously Unknown Simple Cubic Phase in the SnS Binary  
43 System. *Nano Letters* **2015**, *15*, 2174-2179.  
44  
45  
46  
47 69. Abutbul, R. E.; Garcia-Angelmo, A. R.; Burshtein, Z.; Nair, M. T. S.; Nair, P. K.; Golan, Y.,  
48 Crystal Structure of a Large Cubic Tin Monosulfide Polymorph: An Unraveled Puzzle.  
49  
50 *CrystEngComm* **2016**, *18*, 5188-5194.  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

1  
2  
3 70. Yasuhara, S.; Hamasaki, Y.; Katayama, T.; Ao, T.; Inaguma, Y.; Hojo, H.; Karppinen, M.;  
4 Philip, A.; Yasui, S.; Itoh, M., Modulating the Structure and Magnetic Properties of  $\epsilon$ -Fe<sub>2</sub>O<sub>3</sub>  
5 Nanoparticles via Electrochemical Li<sup>+</sup> Insertion. *Inorganic Chemistry* **2020**, *59*, 4357-4365.  
6  
7 71. Blöchl, P. E., Projector Augmented-Wave Method. *Physical Review B* **1994**, *50*, 17953-17979.  
8  
9 72. Kresse, G.; Furthmüller, J., Efficient Iterative Schemes for *ab Initio* Total-Energy  
10 Calculations Using a Plane-Wave Basis Set. *Physical Review B* **1996**, *54*, 11169-11186.  
11  
12 73. Perdew, J. P.; Ruzsinszky, A.; Csonka, G. I.; Vydrov, O. A.; Scuseria, G. E.; Constantin, L.  
13 A.; Zhou, X.; Burke, K., Restoring the Density-Gradient Expansion for Exchange in Solids  
14 and Surfaces. *Physical Review Letters* **2008**, *100*, 136406.  
15  
16 74. Cen, J.; Pallikara, I.; Skelton, J. M., Structural Dynamics and Thermal Transport in Bismuth  
17 Chalcogenide Alloys. *Chemistry of Materials* **2021**, *33*, 8404-8417.  
18  
19 75. Tang, W.; Sanville, E.; Henkelman, G., A Grid-Based Bader Analysis Algorithm without  
20 Lattice Bias. *Journal of Physics: Condensed Matter* **2009**, *21*, 084204.  
21  
22 76. Magnus Rahm, J.; Erhart, P., WulffPack: A Python Package for Wulff Constructions. *Journal  
23 of Open Source Software* **2020**, *5*, 1944.  
24  
25 77. Sun, W.; Kitchaev, D. A.; Kramer, D.; Ceder, G., Non-Equilibrium Crystallization Pathways  
26 of Manganese Oxides in Aqueous Solution. *Nature Communications* **2019**, *10*, 573.  
27  
28 78. Qi, W. H.; Wang, M. P.; Liu, Q. H., Shape Factor of Nonspherical Nanoparticles. *Journal of  
29 Materials Science* **2005**, *40*, 2737-2739.  
30  
31  
32  
33  
34  
35  
36  
37  
38  
39  
40  
41  
42  
43  
44  
45  
46  
47  
48  
49  
50  
51  
52  
53  
54  
55  
56  
57  
58  
59  
60

## TOC graphic

